
ANALYTICAL METHODS FOR CHARACTERIZATION OF NANOMATERIALS

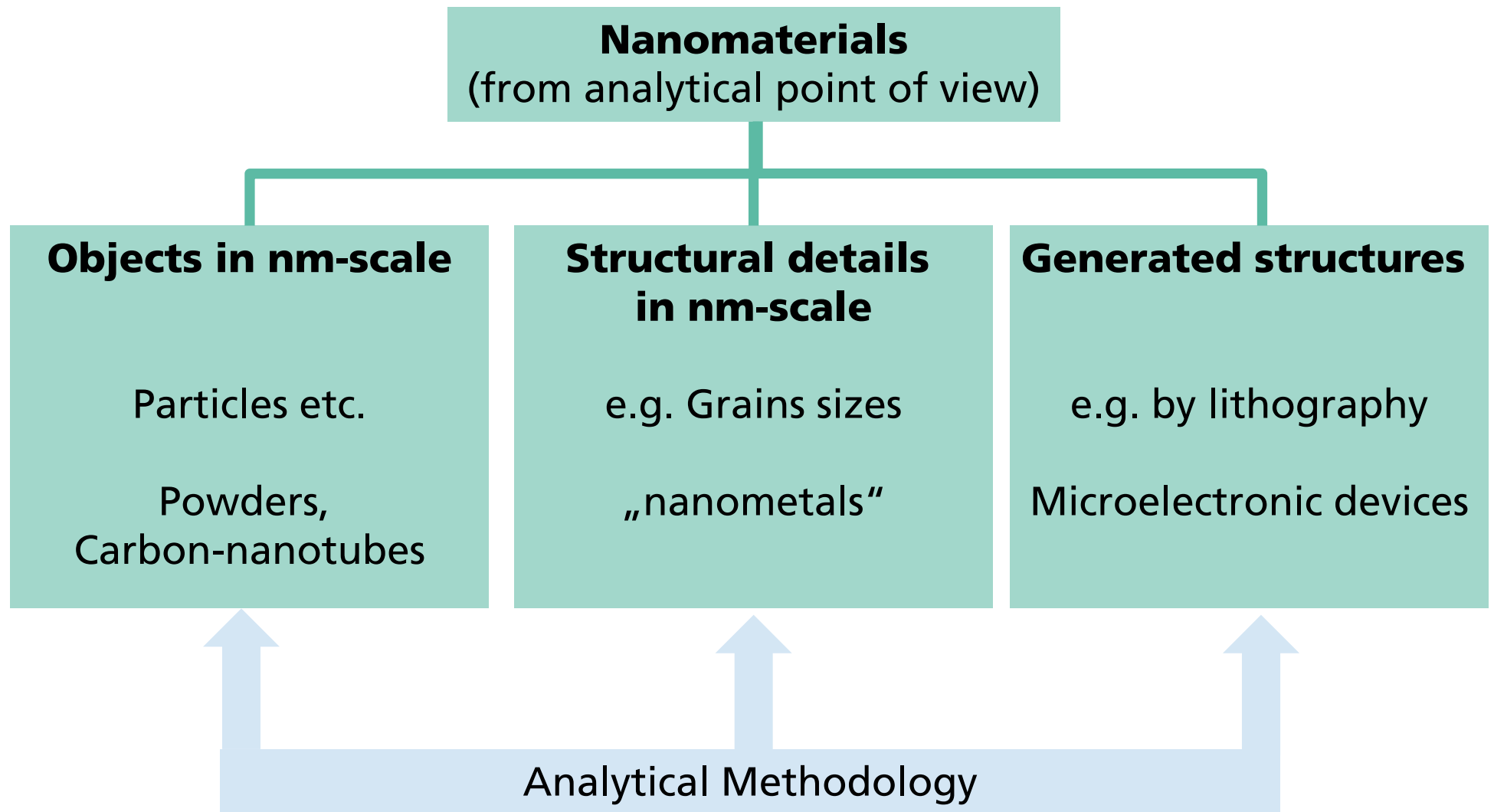
Dr. Ing. habil. Uwe Muehle



Outline

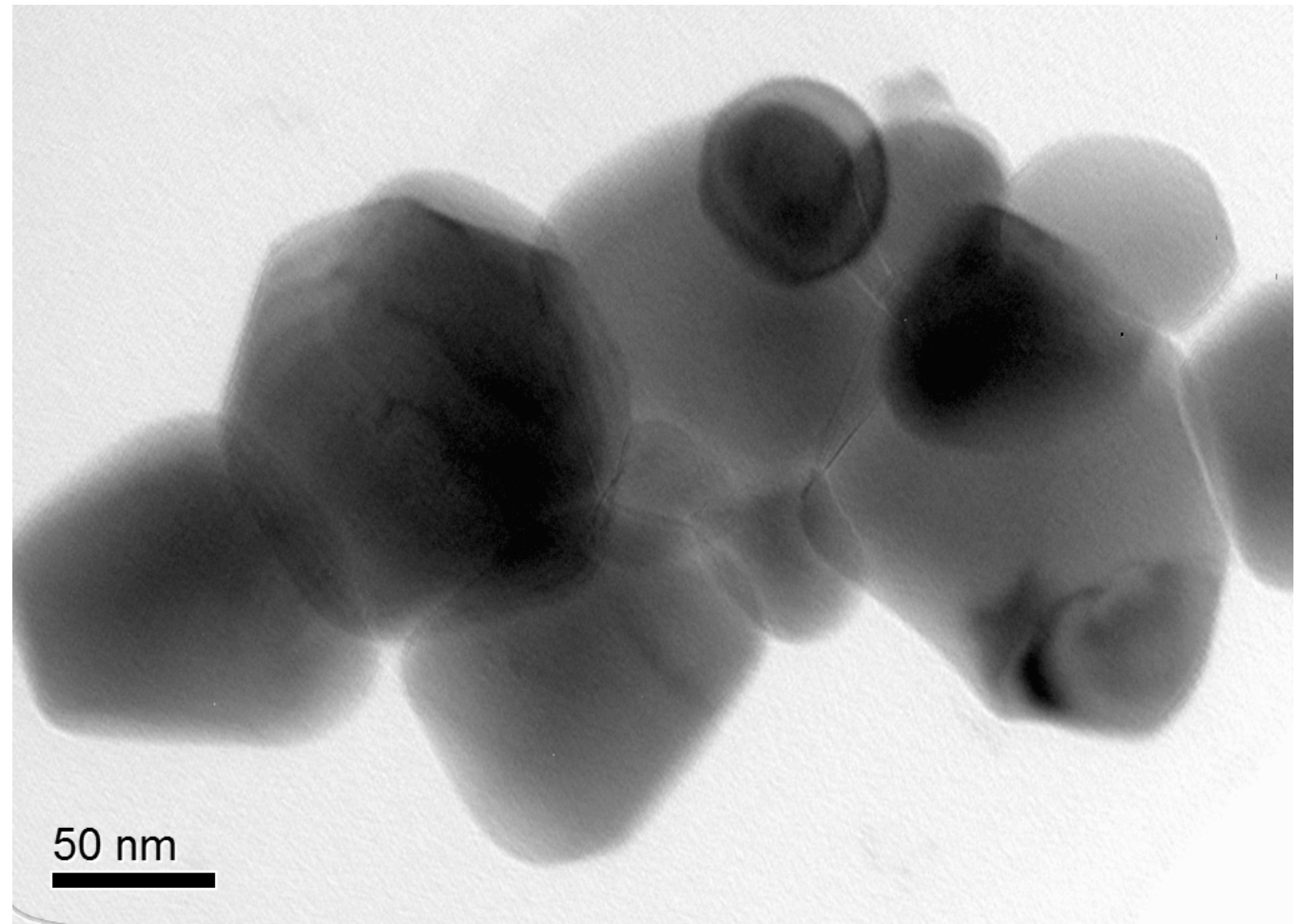
- Introduction, Targets of characterization
 - Size, shape, structure, chemistry, crystallography
- Imaging methods
 - Electron microscopy, Ion microscopy, Atomic force microscopy
- Elemental and structural analysis
 - X-ray spectroscopy, Electron spectroscopy, X-Ray diffraction
- Summary and prospectives

Analytical methods for characterization of nanomaterials



Powders, Particles etc.

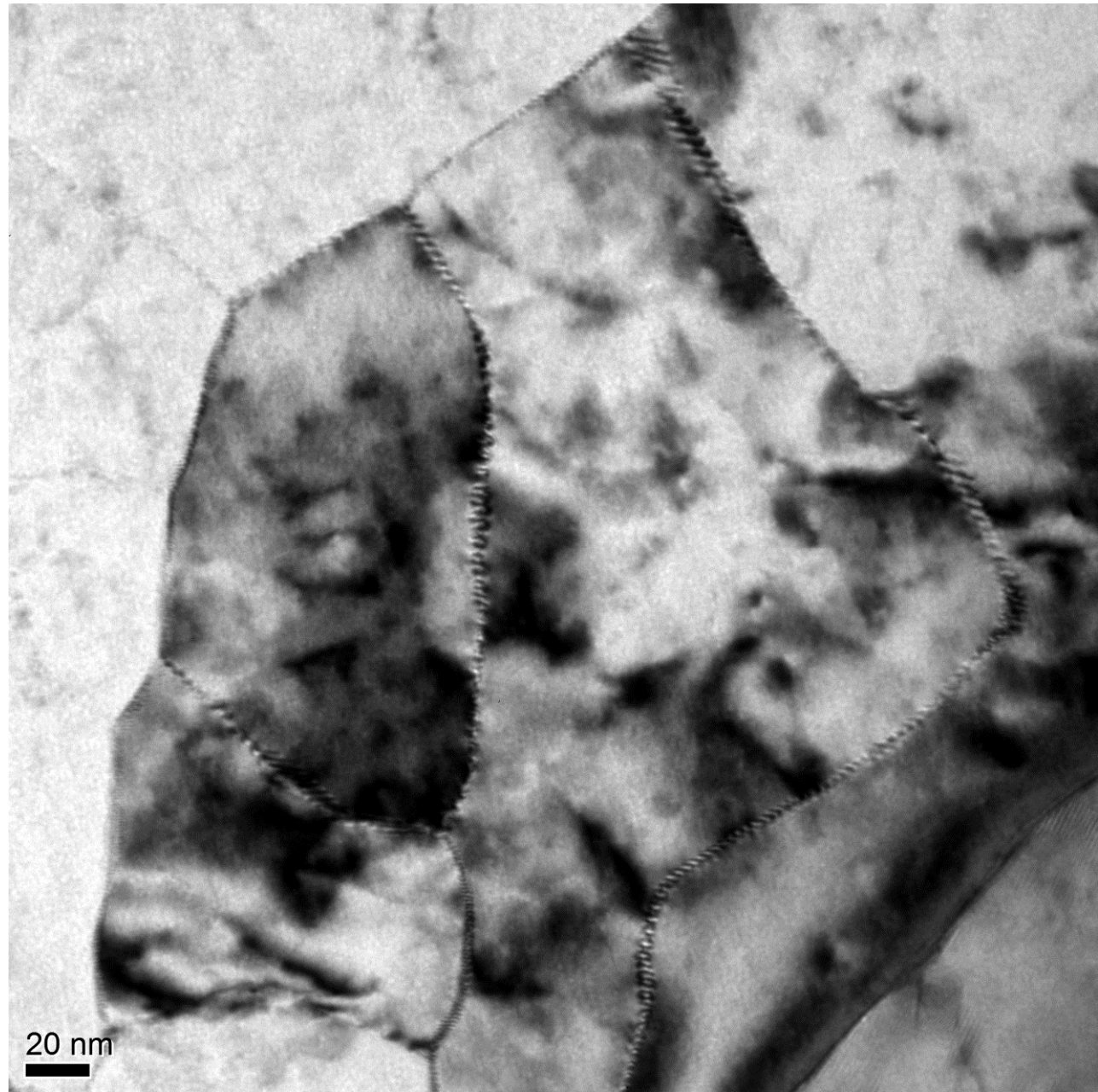
TiAlN-
Particles etc.



Structural details in nm-scale

e.g. Grains sizes
„nanometals“

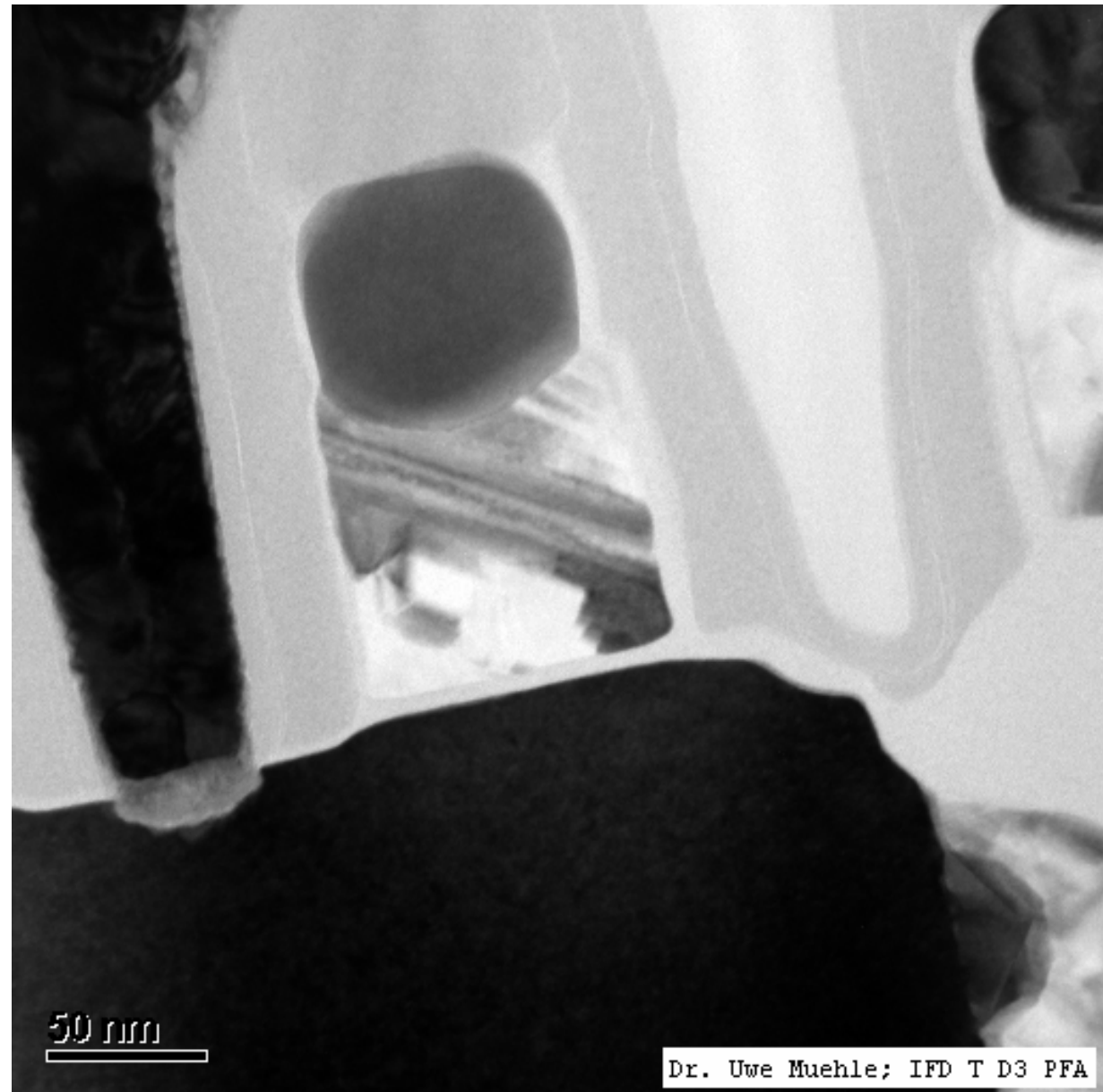
Here: Al-alloy after
high pressure
deformation



Generated structures

e.g. by lithography

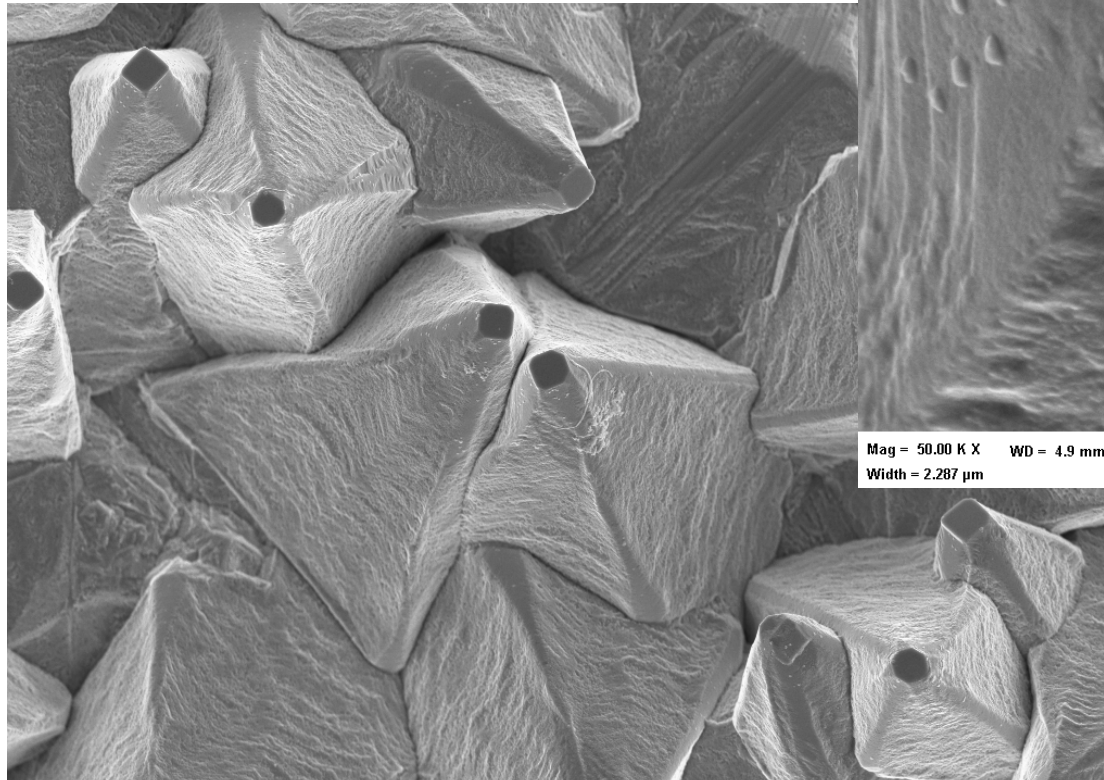
Microelectronic devices:
Transistor of a DRAM
memory cell



Target of analysis

Particles and Carbon nanowire on an structured copper substrate

Size

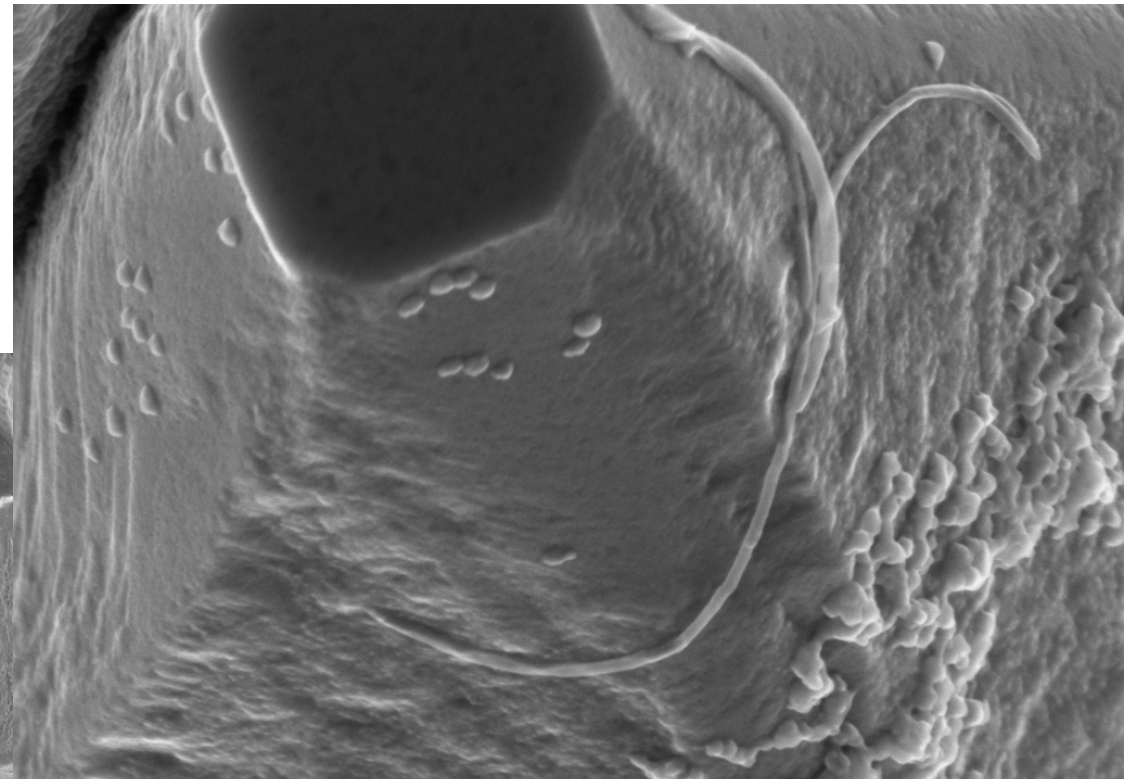


Mag = 5.00 K X WD = 4.9 mm
Width = 22.87 μm

1 μm^*

SEM

EHT = 5.00 kV Signal A = InLens Date :12 Oct 2011 Time :8:53:30
FIB Probe = 30KV:80 pA Signal B = SESI System Vacuum = 1.77e-006 mbar



Mag = 50.00 K X WD = 4.9 mm
Width = 2.287 μm

200 nm*

SEM

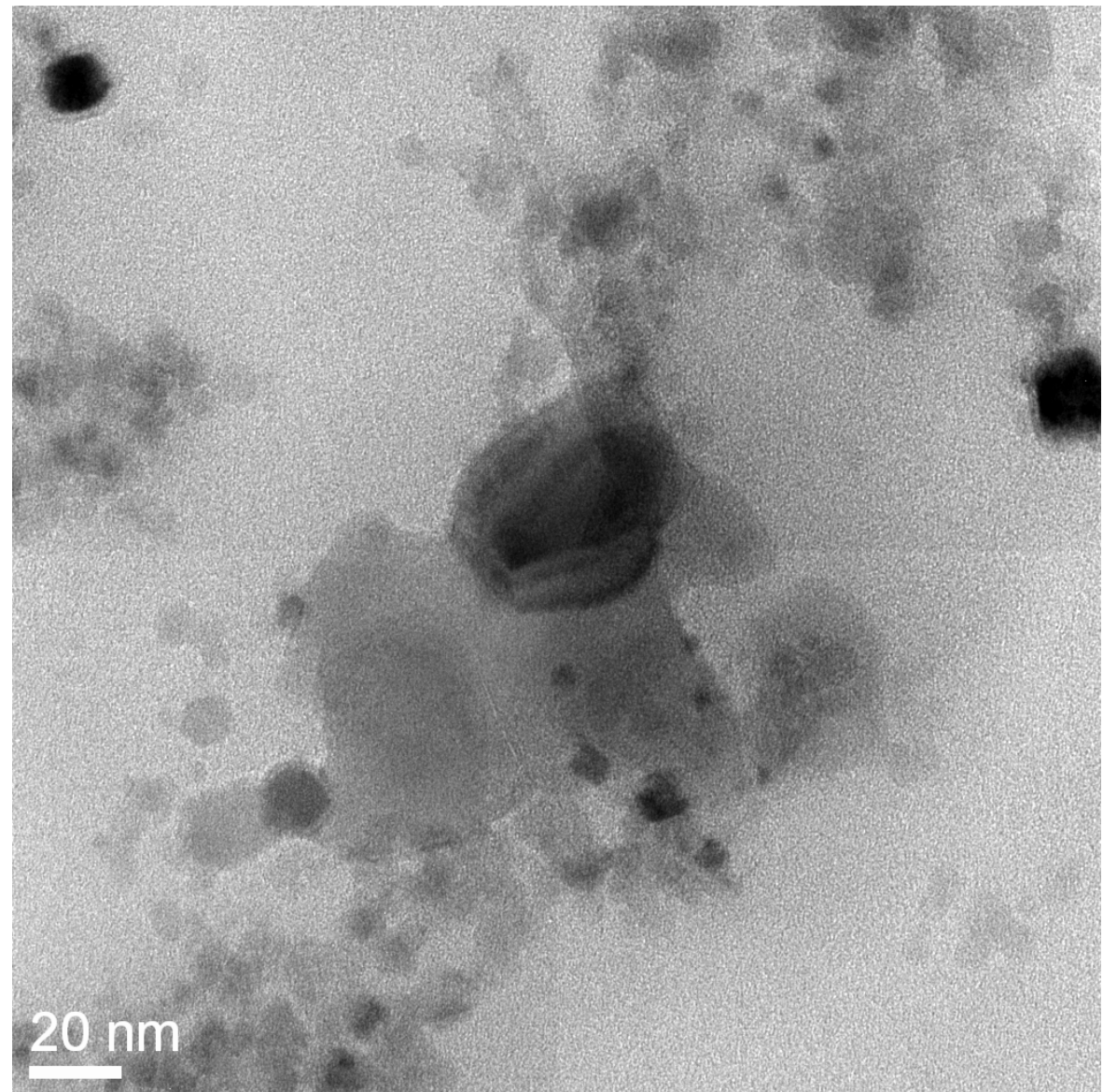
EHT = 5.00 kV Signal A = InLens Date :12 Oct 2011 Time :8:58:27
FIB Probe = 30KV:80 pA Signal B = SESI System Vacuum = 1.66e-006 mbar

Target of analysis

Size

TiCN-particles:

Different fractures of size
(+ shape and internal
structure)

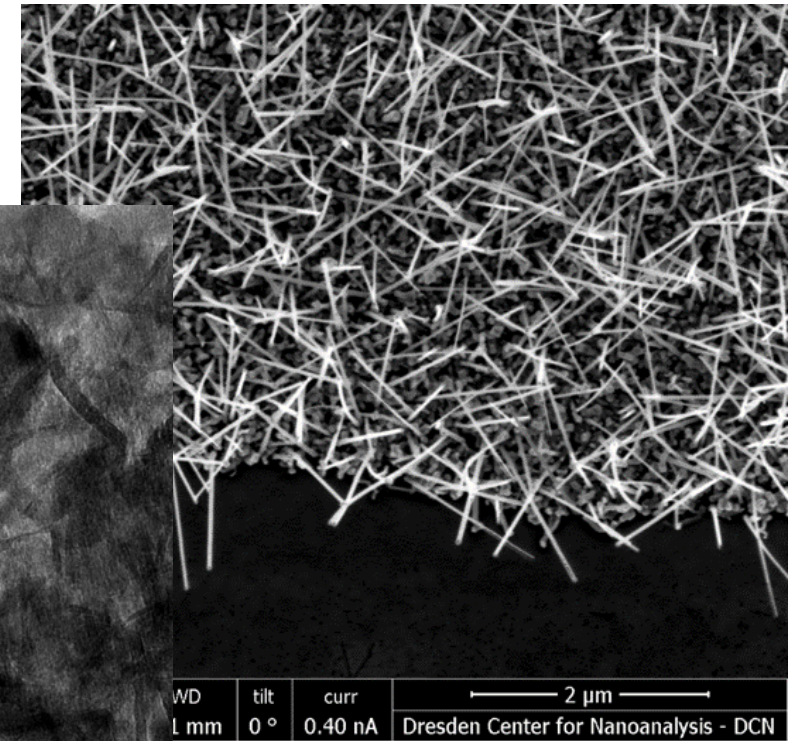
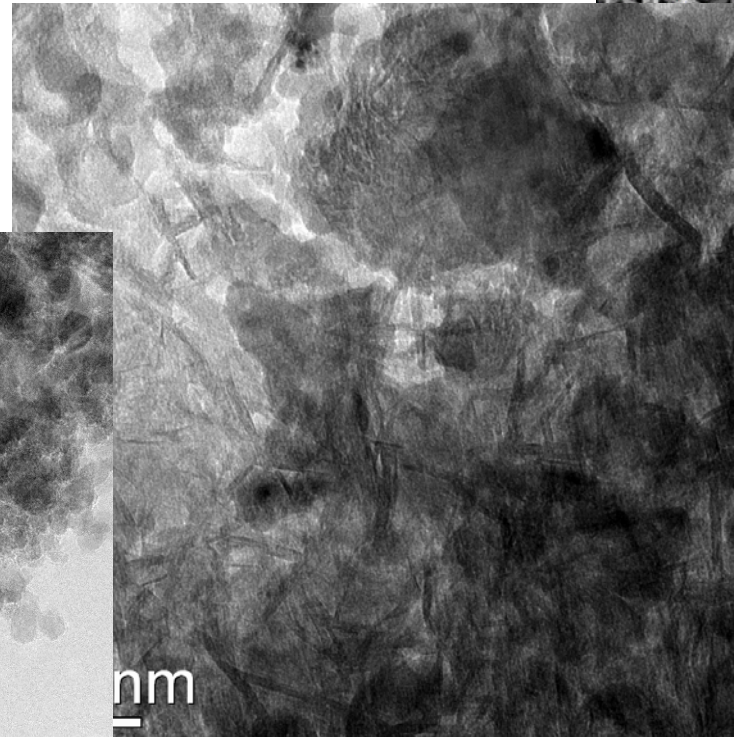
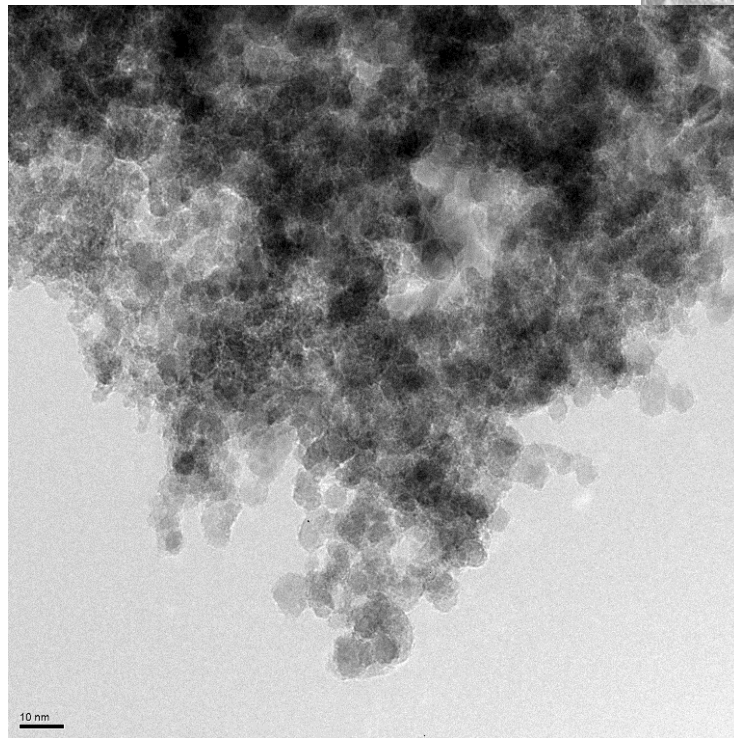


Analytical methods for characterization of nanomaterials

Target of analysis

Globular: Nanodiamonds, left
Needles: AlN, centre
Fibres: Si-nanowire, right

Shape

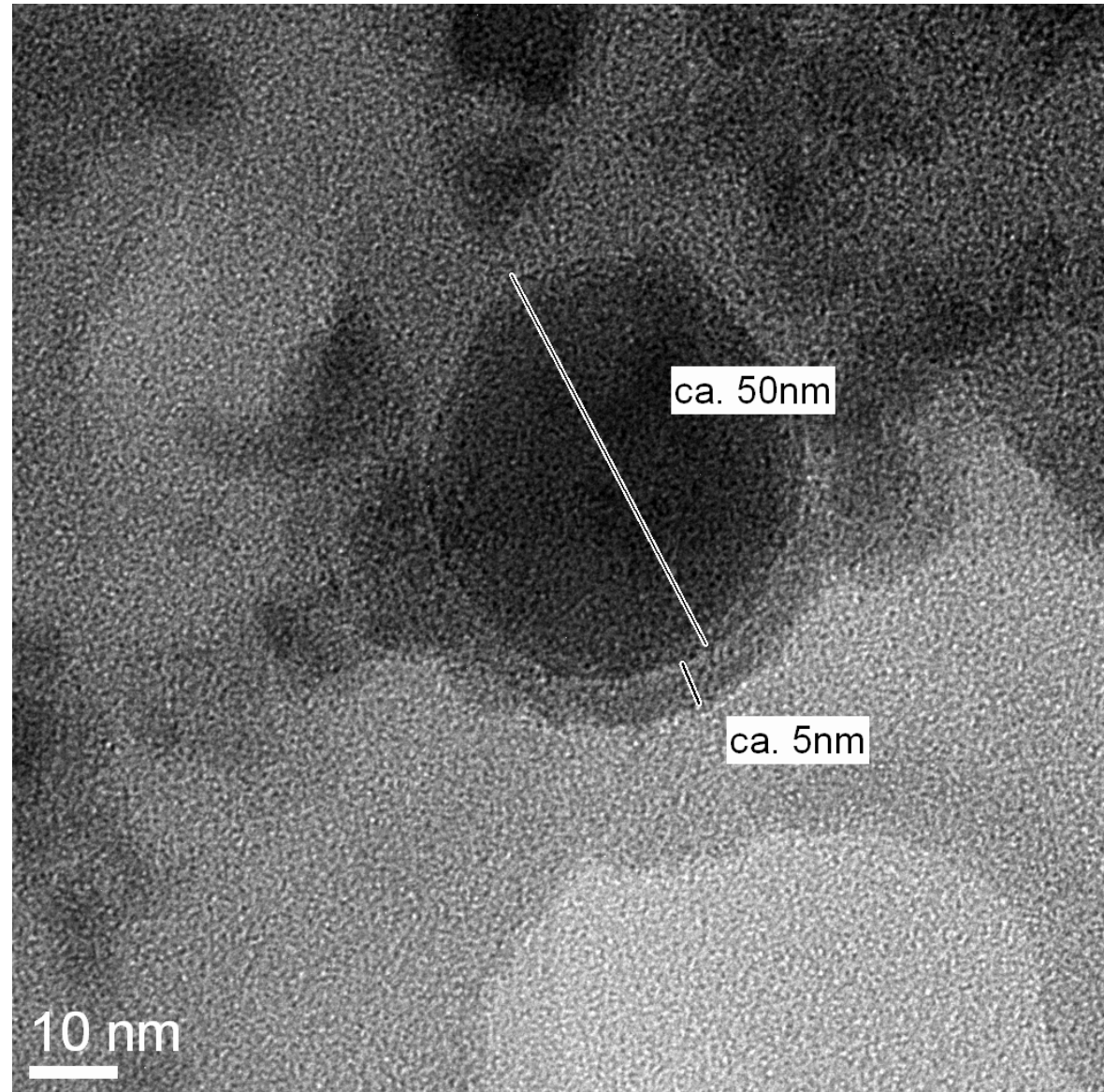


Target of analysis

Structure

Core-Shell-structure:

TiCN-Particle with oxidic shell
(amorphous)

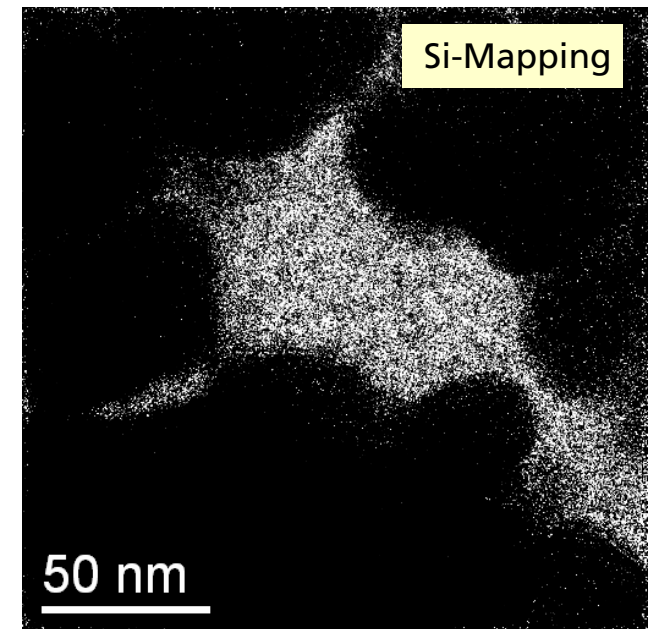
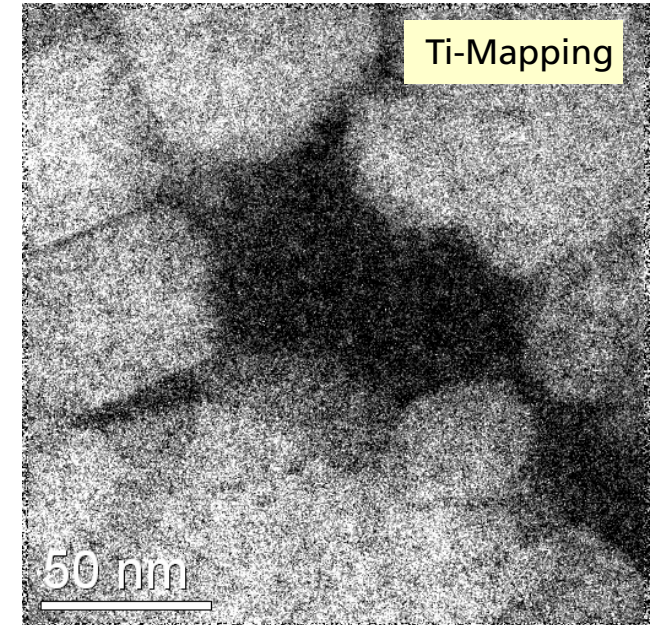
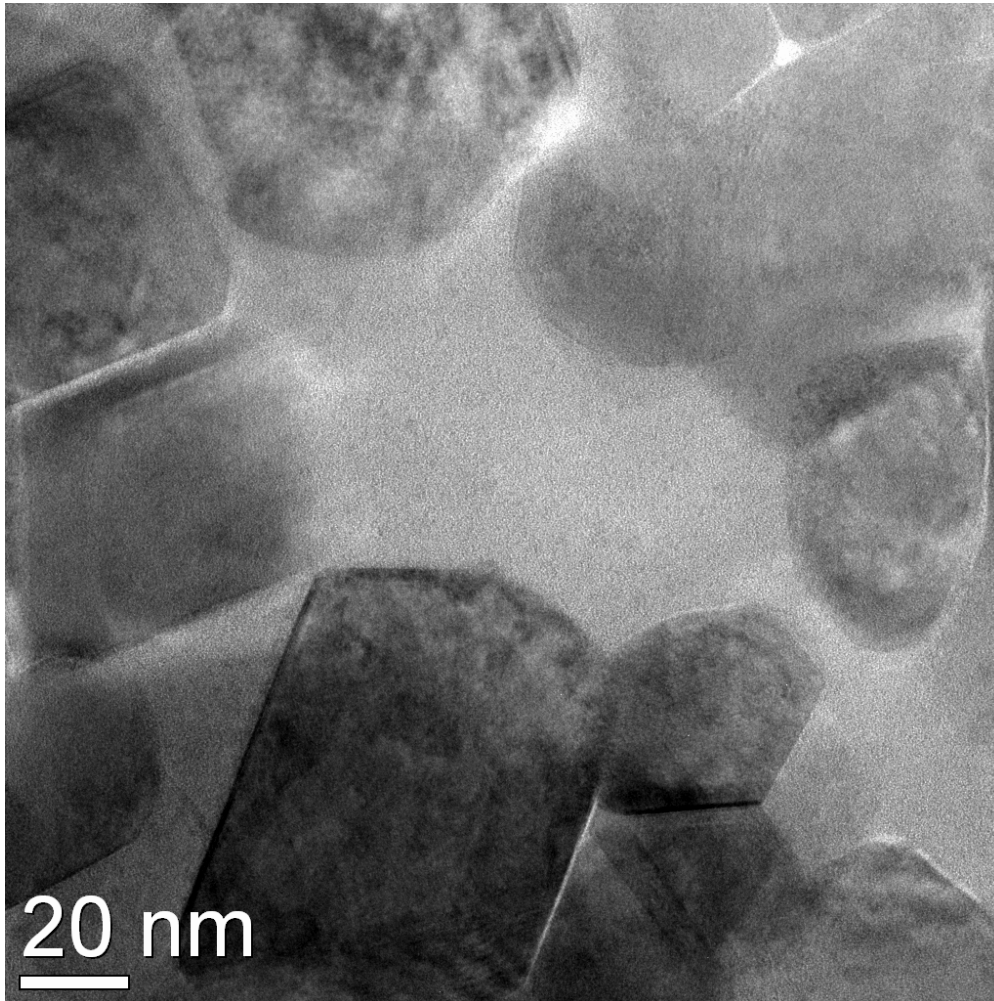


Analytical methods for characterization of nanomaterials

Target of analysis

Chemistry

Sintered material: TiN/Si₃N₄

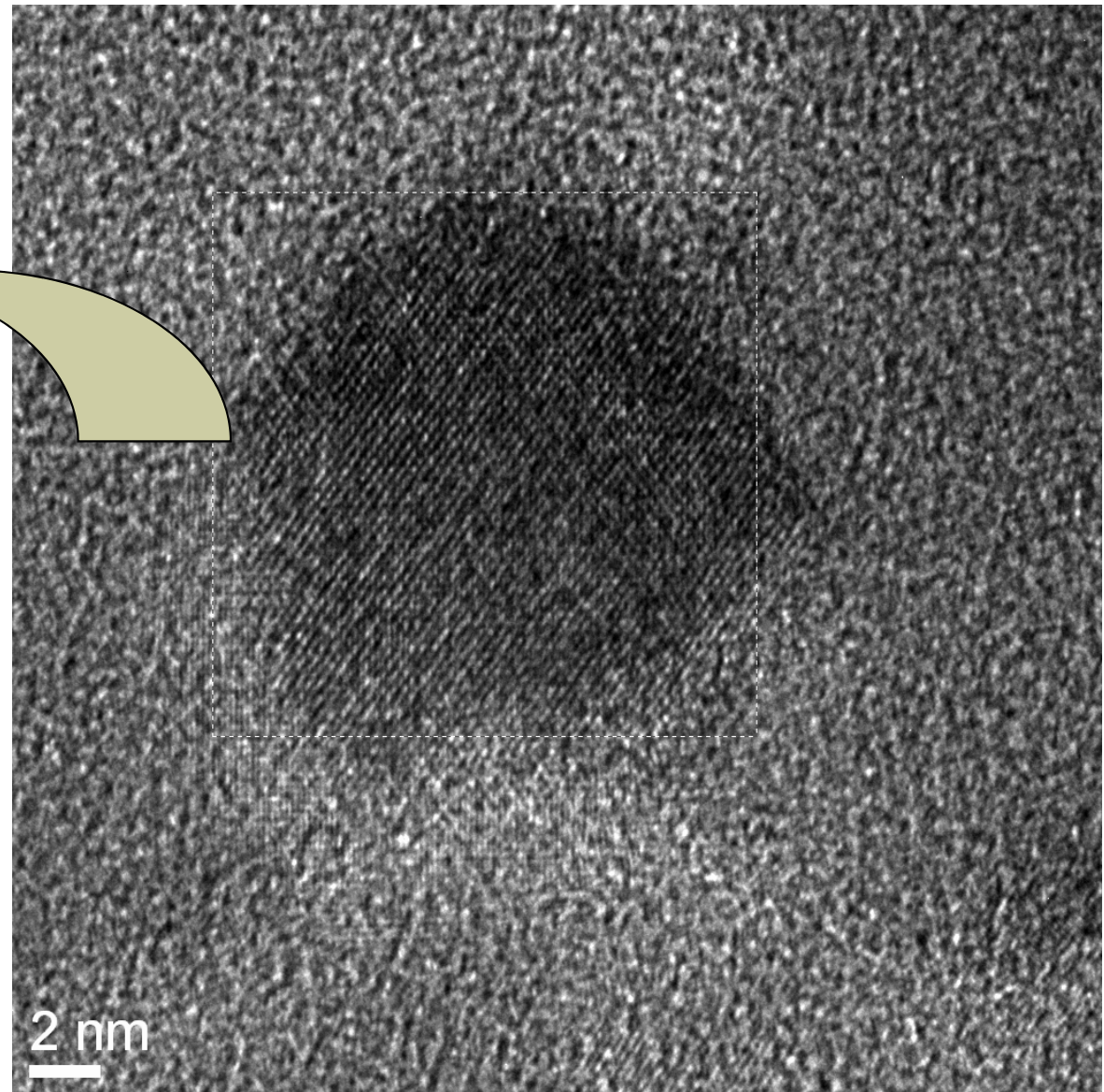
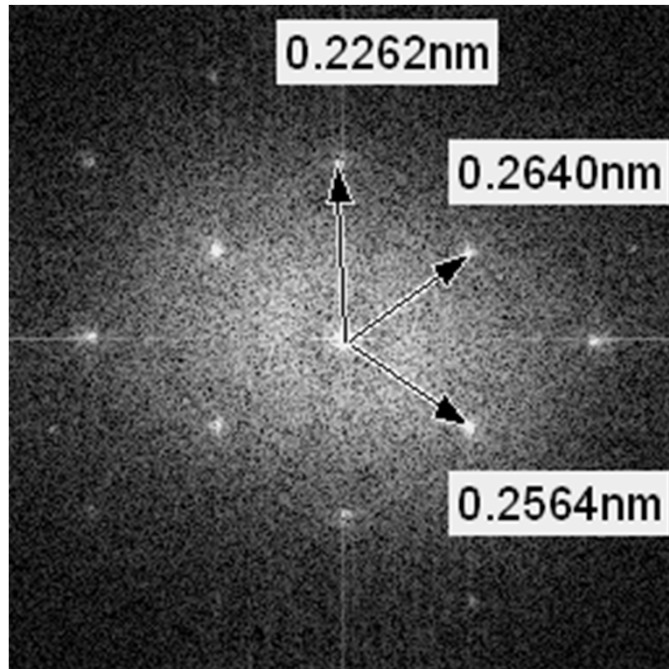
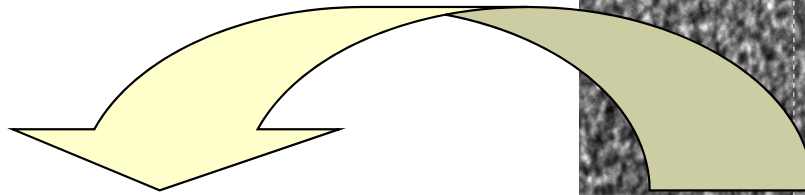


Target of analysis

Crystallography

TiCN-Particle in HRTEM (right)

Fouriertransformation (low)
identifies fcc-structure

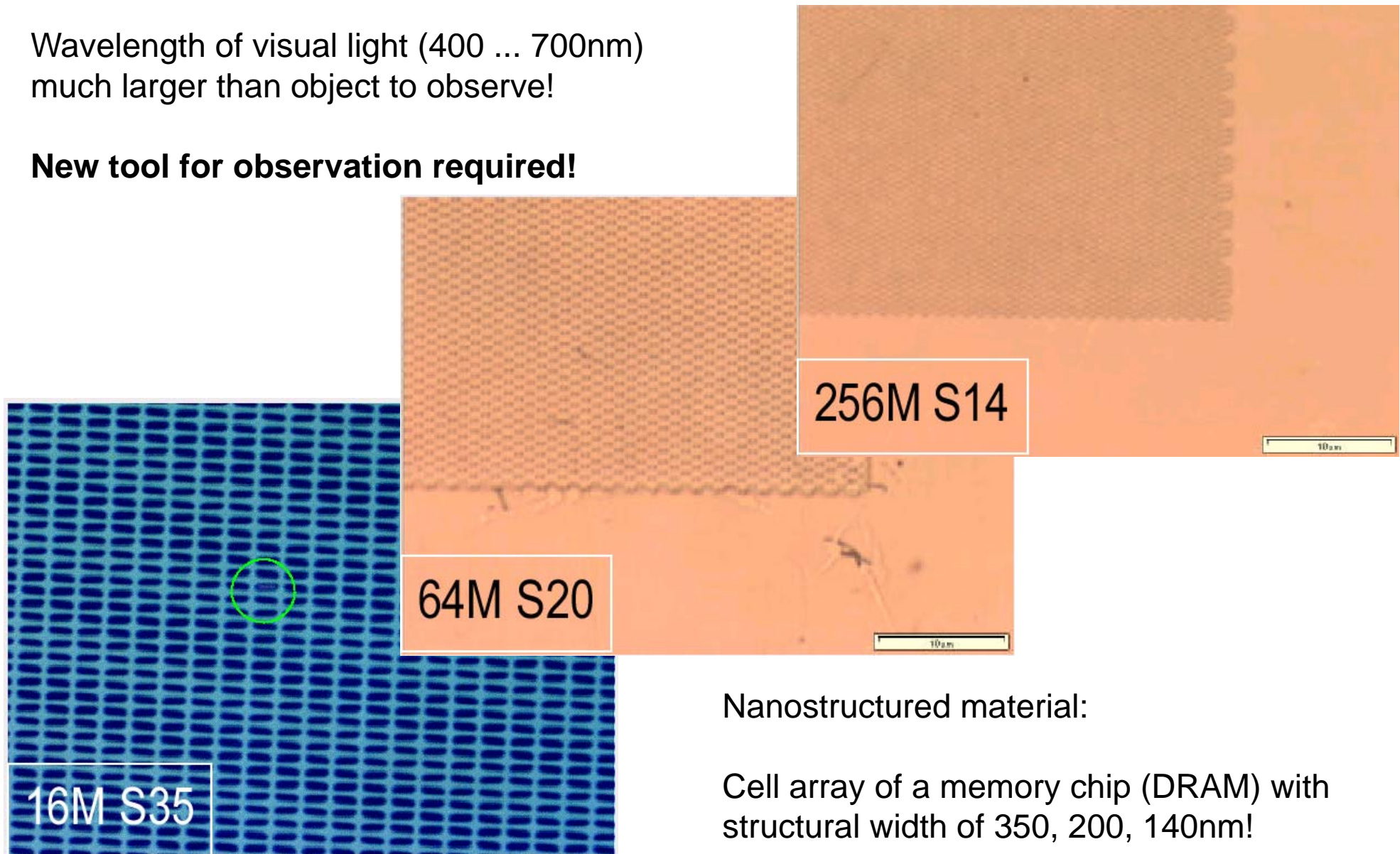


Methods of analysis

Imaging: Visual light microscopy

Wavelength of visual light (400 ... 700nm)
much larger than object to observe!

New tool for observation required!



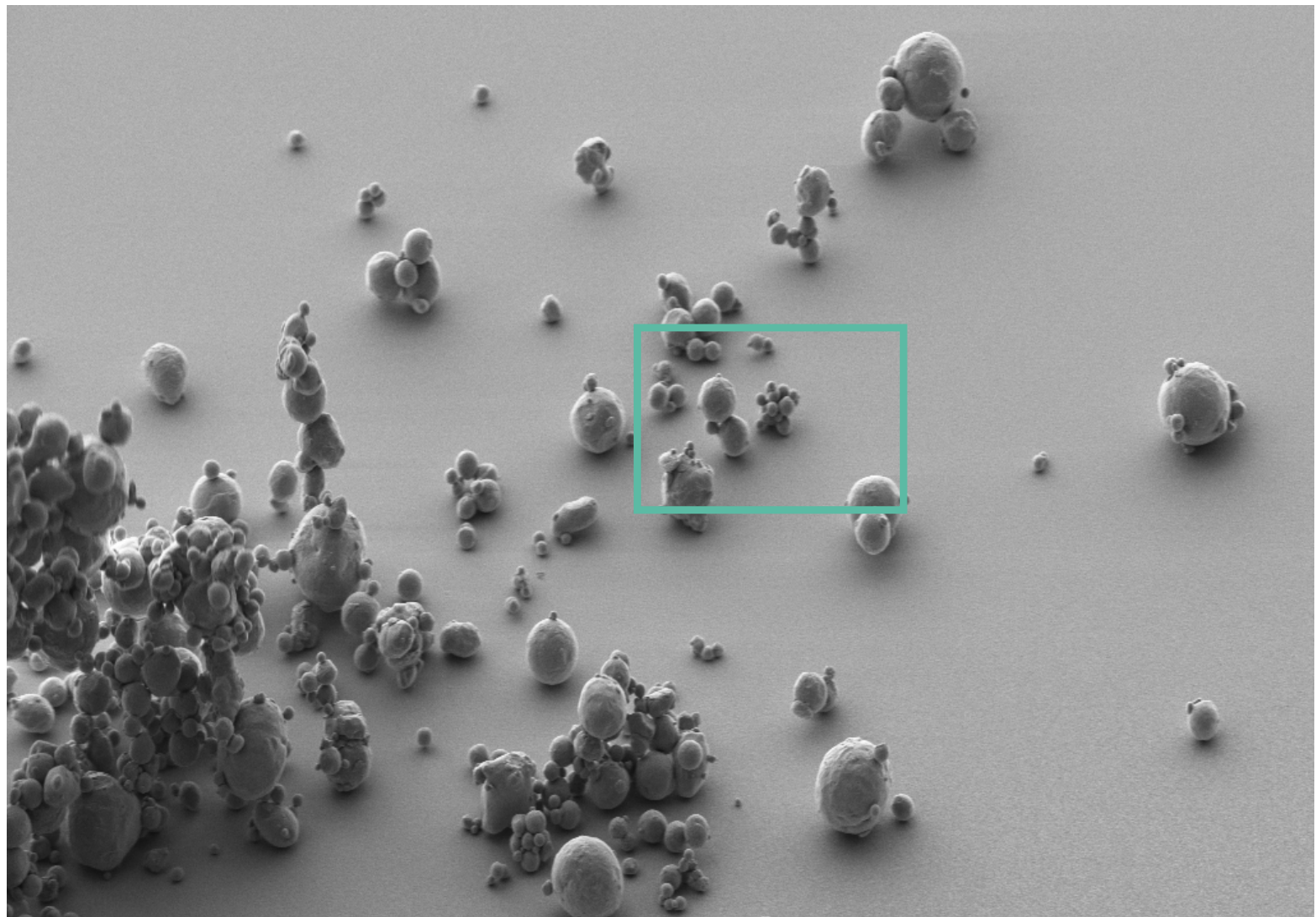
Nanostructured material:

Cell array of a memory chip (DRAM) with
structural width of 350, 200, 140nm!

Methods of analysis Imaging: Scanning electron microscopy

Cu-powder:

Particle size
from several
 μm down to...



Mag = 1.00 K X WD = 4.9 mm
Width = 113.9 μm

10 μm

SEM

EHT = 2.00 kV
FIB Probe = 30KV:80 pA

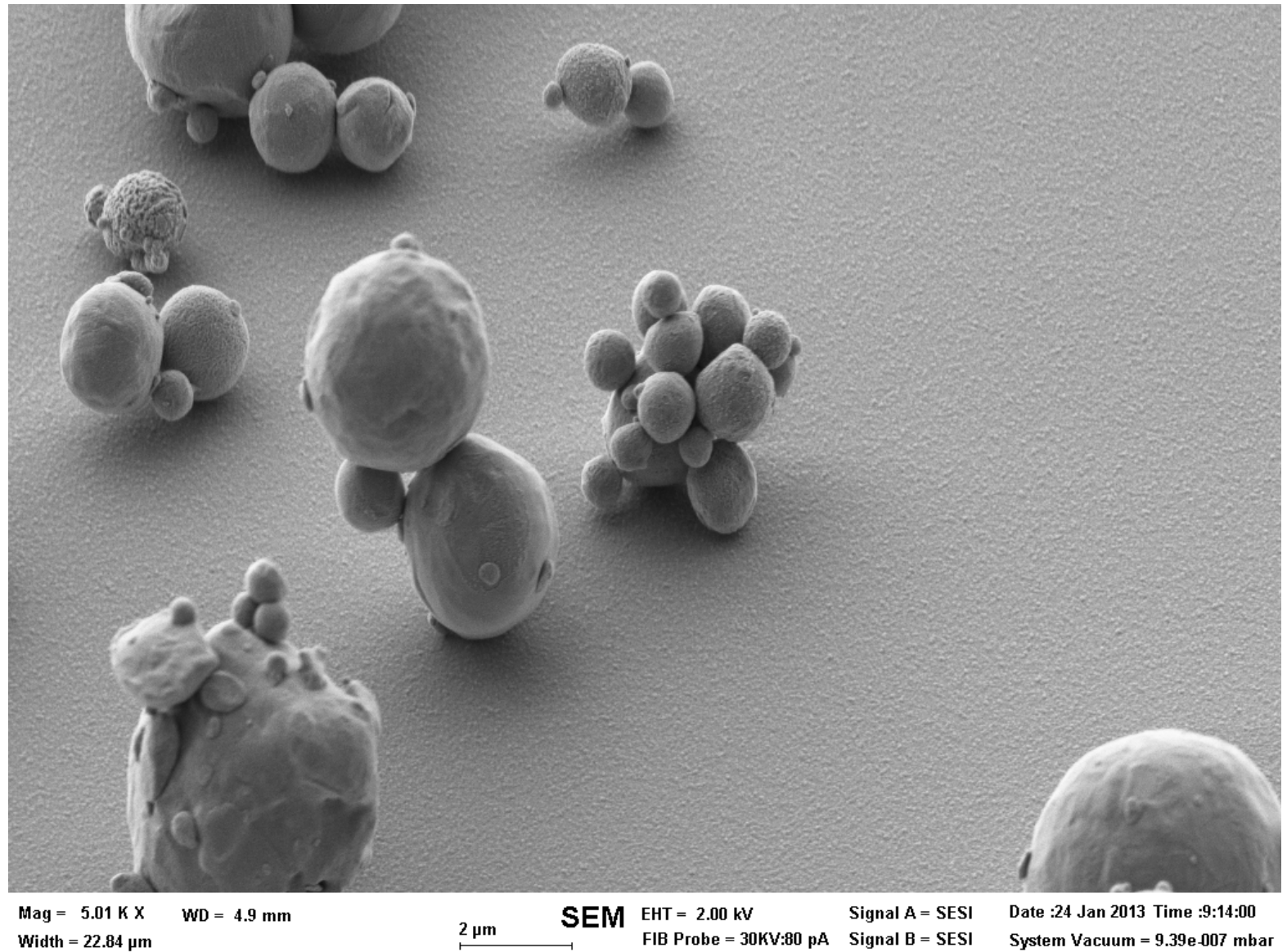
Signal A = SESI
Signal B = SESI

Date :24 Jan 2013 Time :9:12:29
System Vacuum = 9.44e-007 mbar

Methods of analysis Imaging: Scanning electron microscopy

Cu-powder:

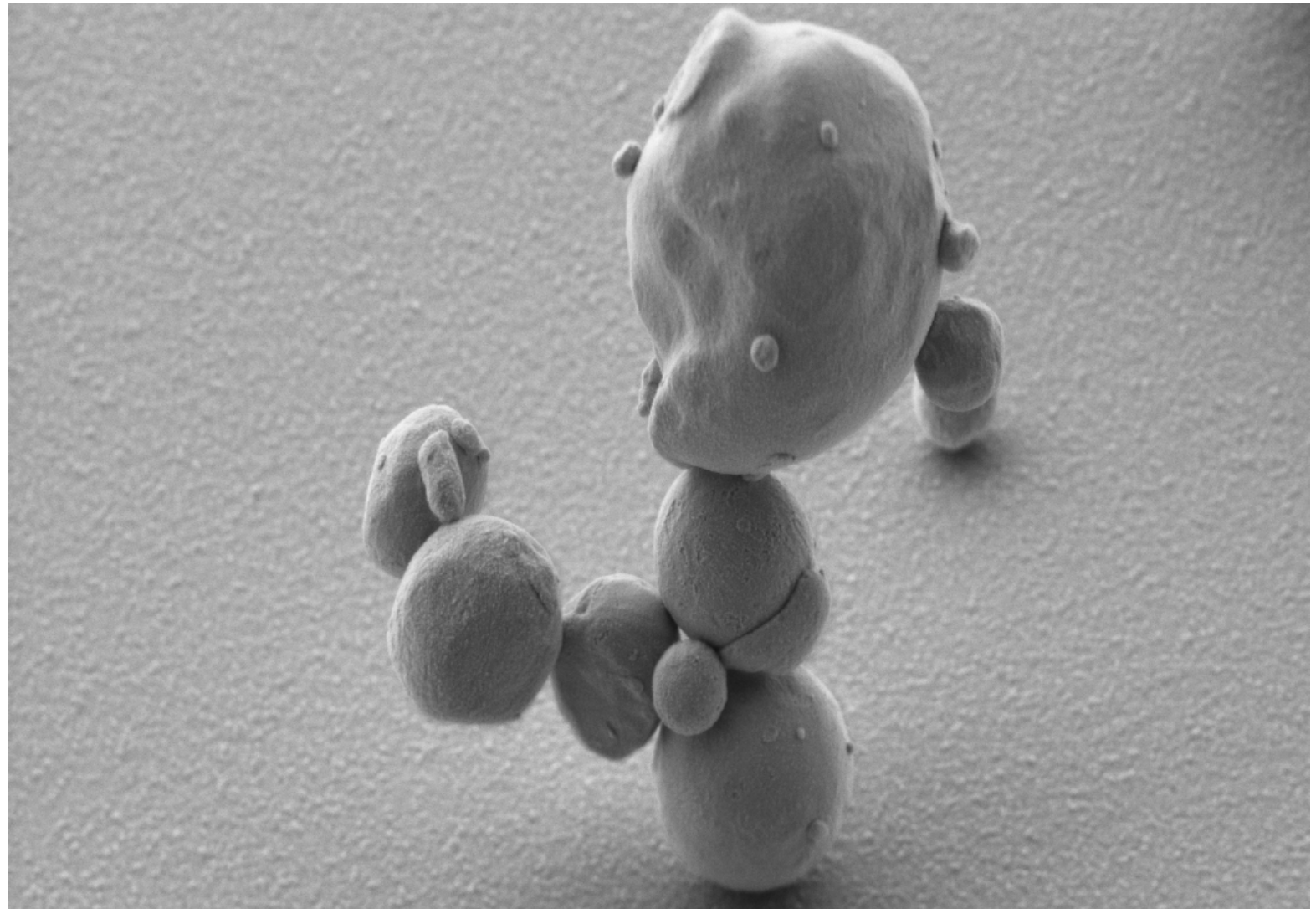
Particle size
in single μm
down to ...



Methods of analysis Imaging: Scanning electron microscopy

Cu-powder:

Particle size
in single μm
down to ...



Mag = 9.01 K X WD = 4.9 mm
Width = 12.69 μm

1 μm

SEM

EHT = 2.00 kV
FIB Probe = 30KV:80 pA

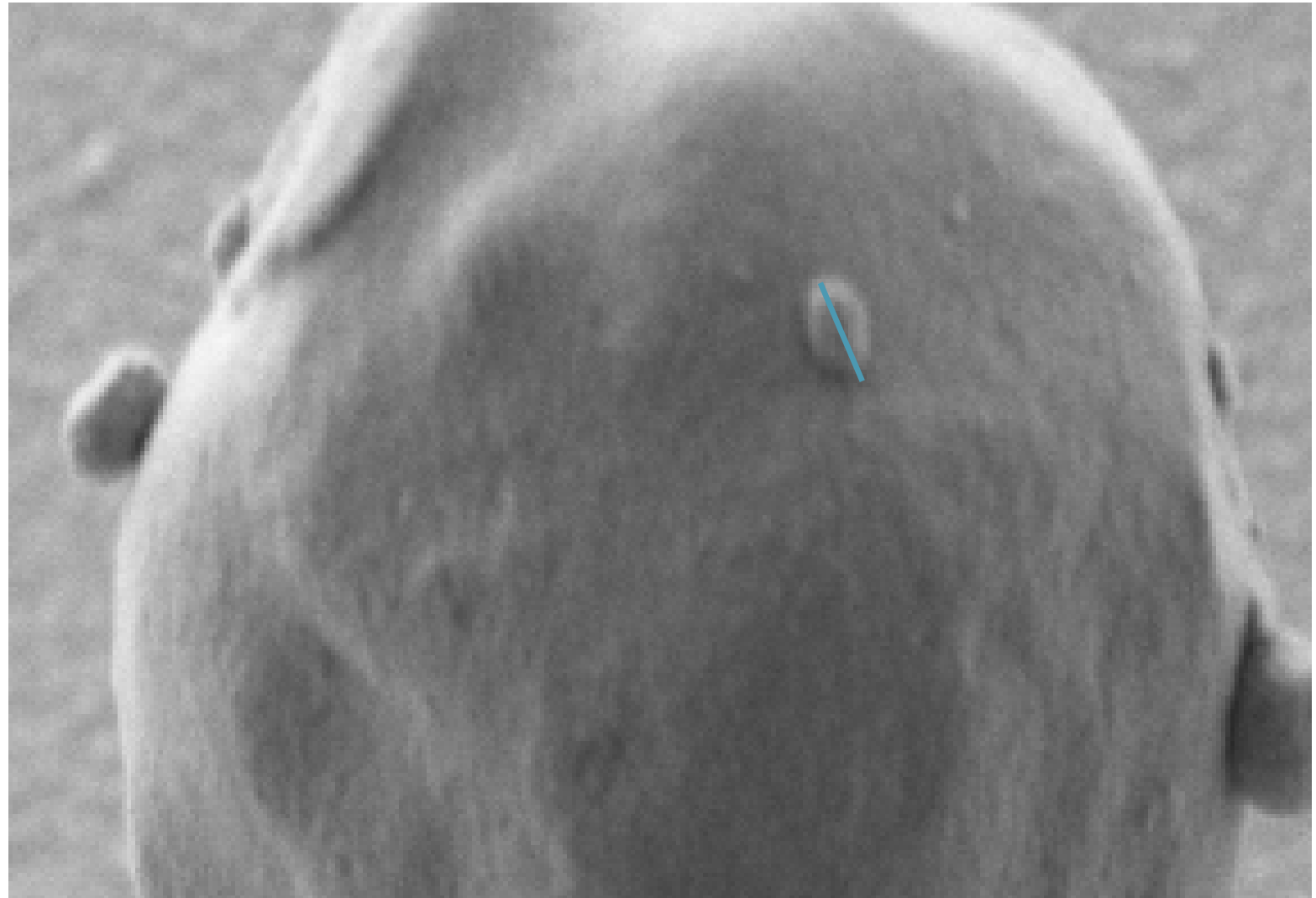
Signal A = SEI
Signal B = SEI

Date :24 Jan 2013 Time :9:18:02
System Vacuum = 1.03e-006 mbar

Methods of analysis Imaging: Scanning electron microscopy

Cu-powder:

Particle size
from single
 μm down to
63nm

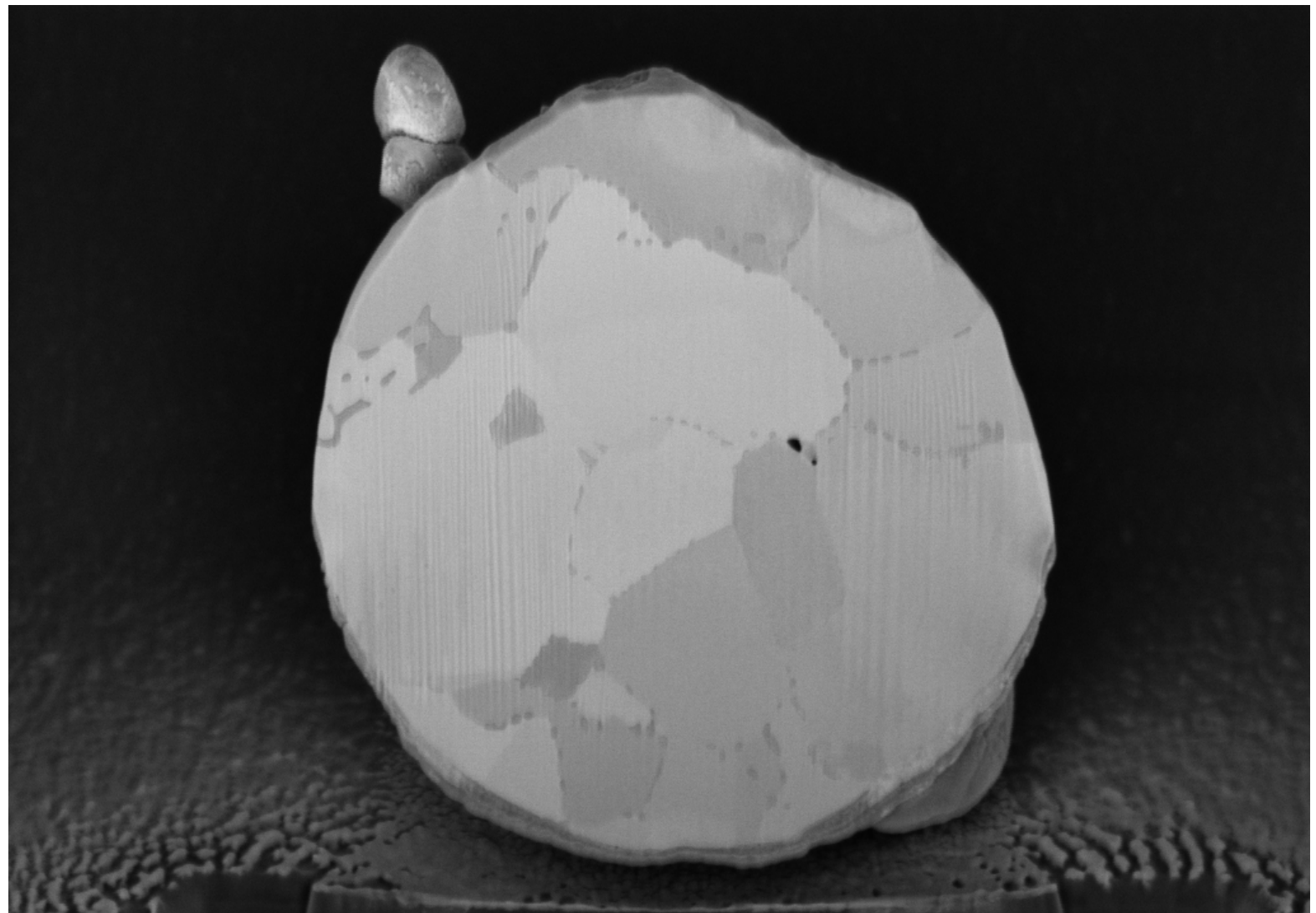


Methods of analysis

Imaging: Focused Ion Beam Technique

Cu-powder:

Internal
structure of
particles



Mag = 13.80 K X WD = 4.8 mm
Width = 8.287 μ m

1 μ m

SEM

EHT = 2.00 kV
FIB Probe = 30KV:80 pA

Signal A = InLens
Signal B = SEI

Date :24 Jan 2013 Time :10:09:09
System Vacuum = 1.05e-006 mbar

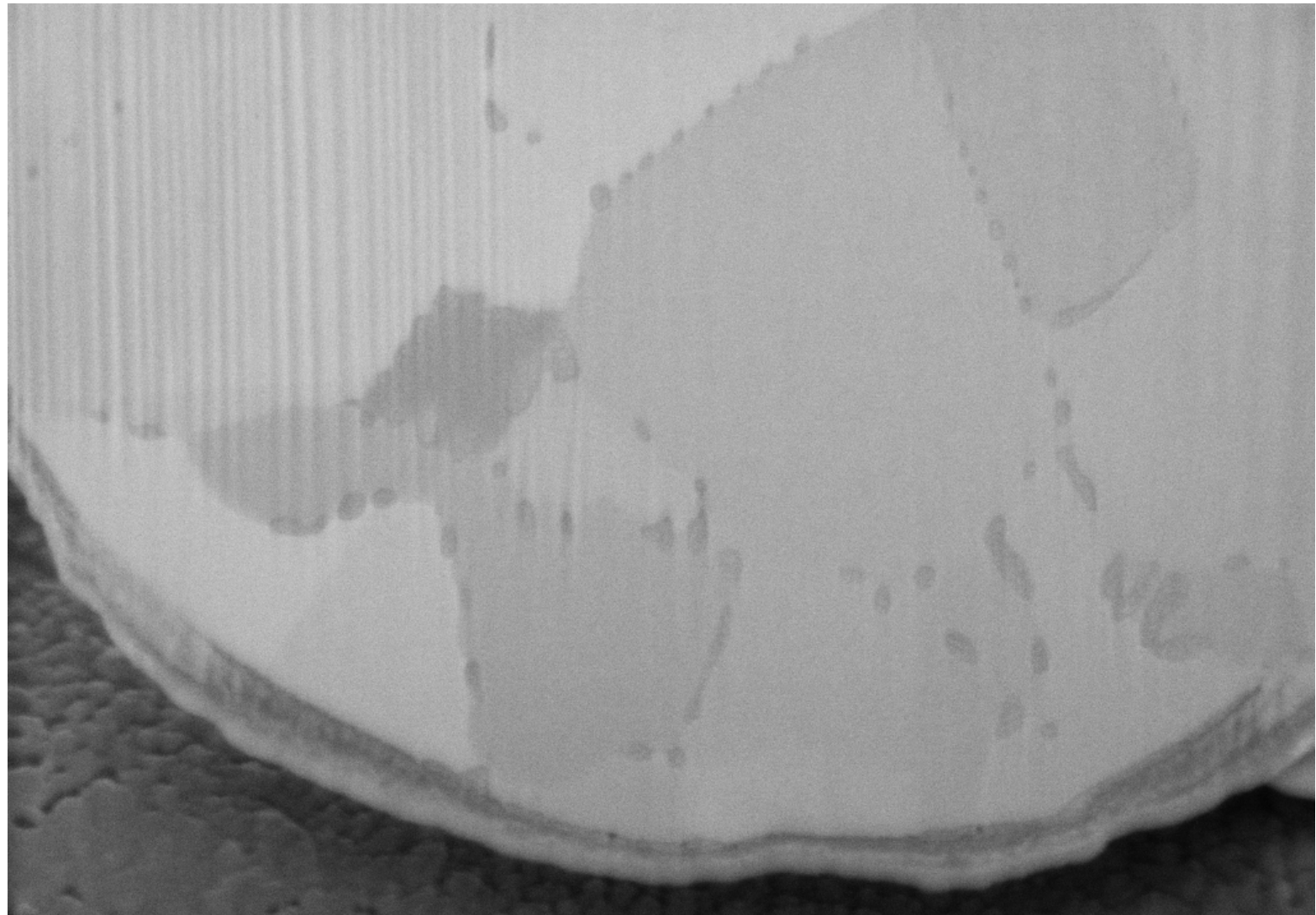
Methods of analysis

Imaging: Focused Ion Beam Technique

Cu-powder:

Internal structure of particles:

- a) Core-shell-structure
- b) Precipitations at grain boundaries



Mag = 35.17 K X WD = 4.8 mm
Width = 3.251 μ m

200 nm

SEM

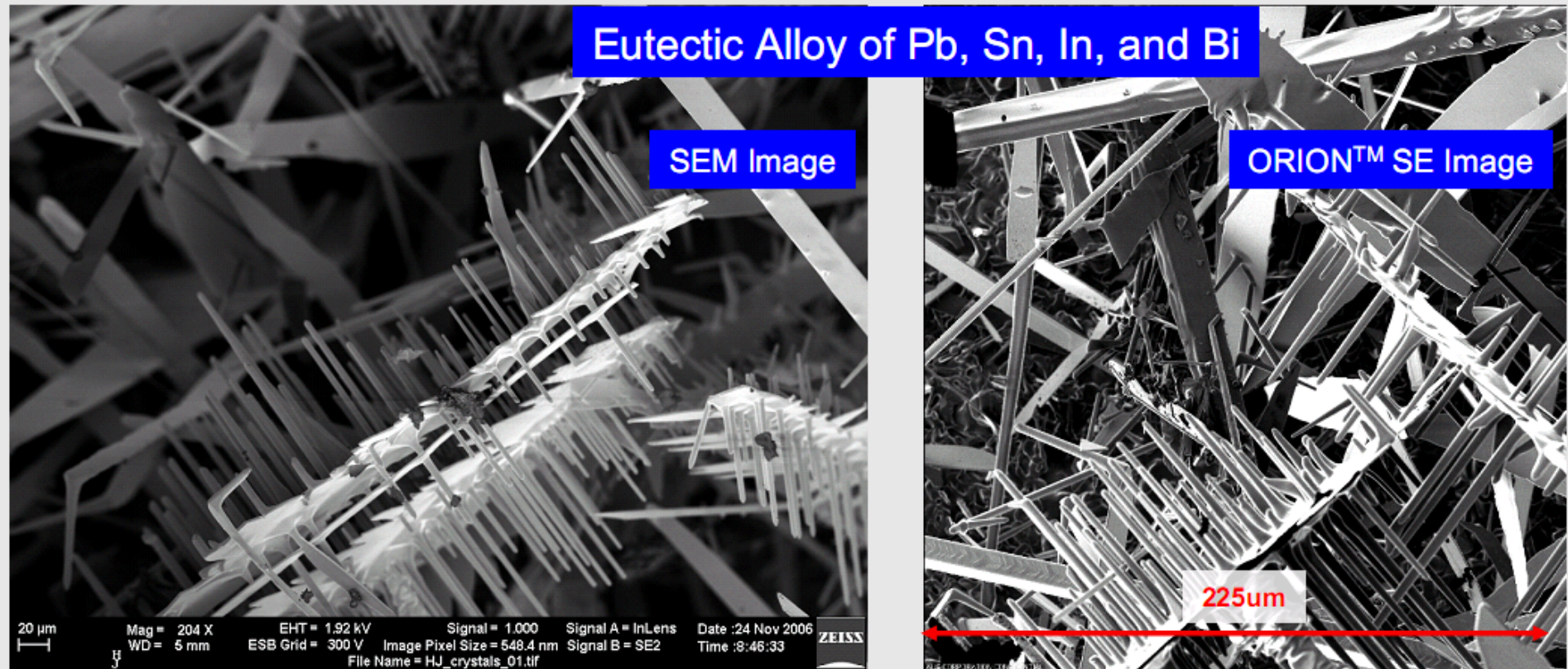
EHT = 2.00 kV
FIB Probe = 30KV:80 pA

Signal A = InLens
Signal B = SESI

Date :24 Jan 2013 Time :10:17:44
System Vacuum = 9.60e-007 mbar

Methods of analysis

Imaging: Helium Ion Microscopy



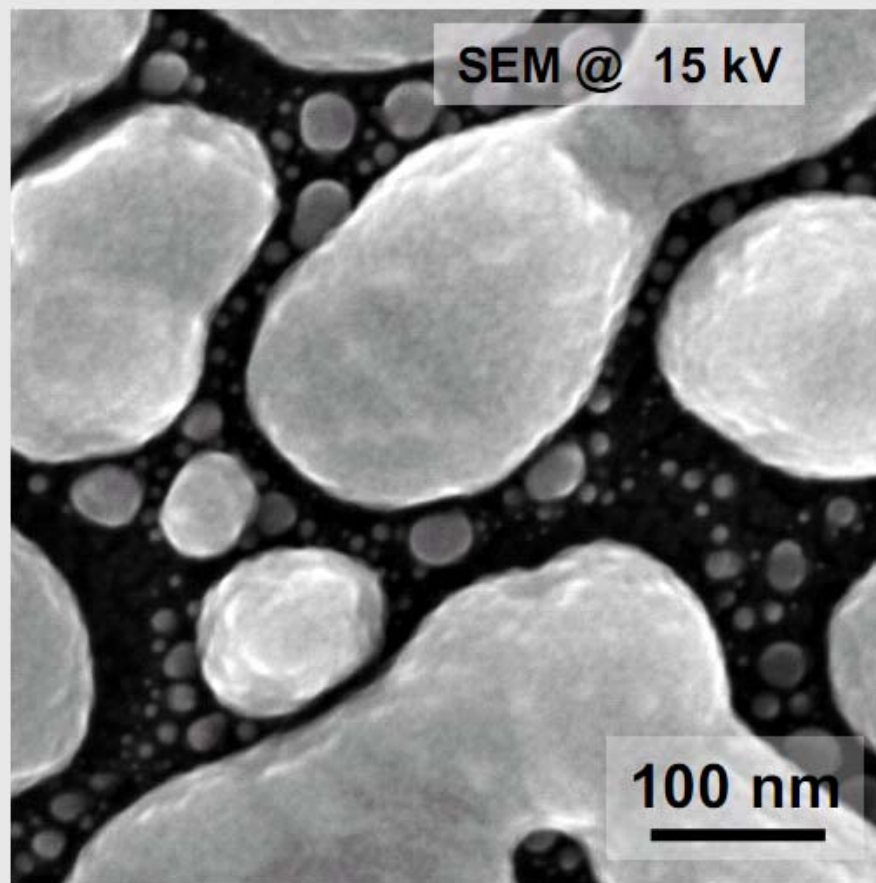
Depth of Field inversely proportional to Half Angle (α_i) of incident beam

Half Angle (α_i) for Orion typically 20 times smaller than for a SEM

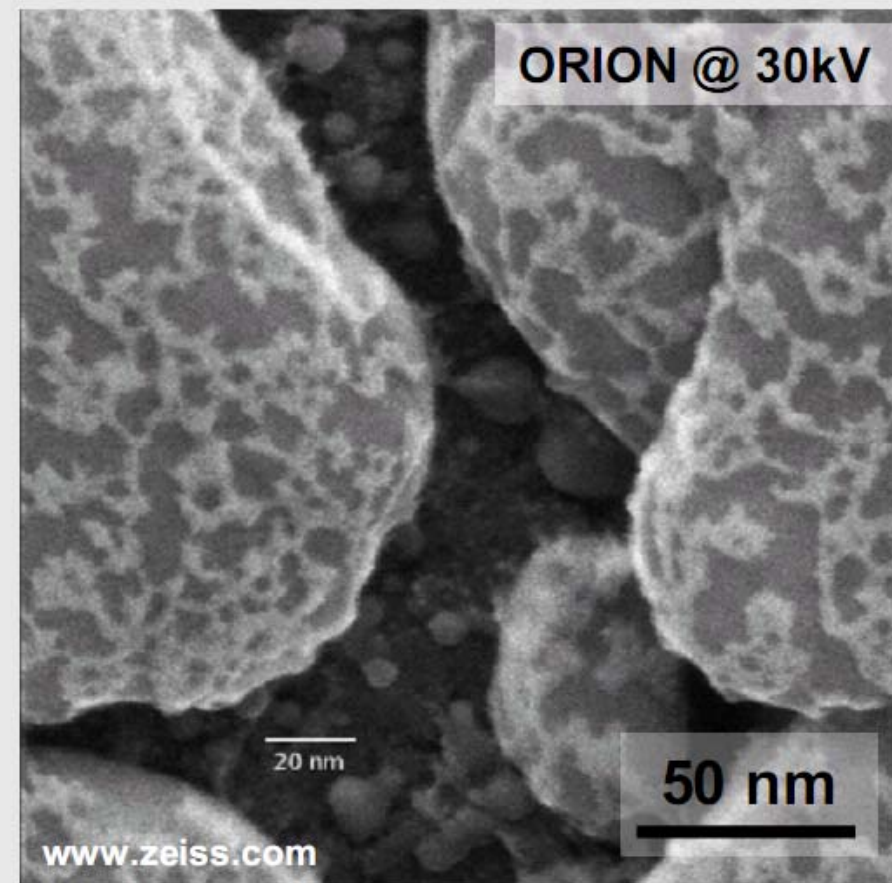
Courtesy: Carl Zeiss NTS, P. Gnauck

Methods of analysis

Imaging: Helium Ion Microscopy



- good SNR
- high contrast between Au and C

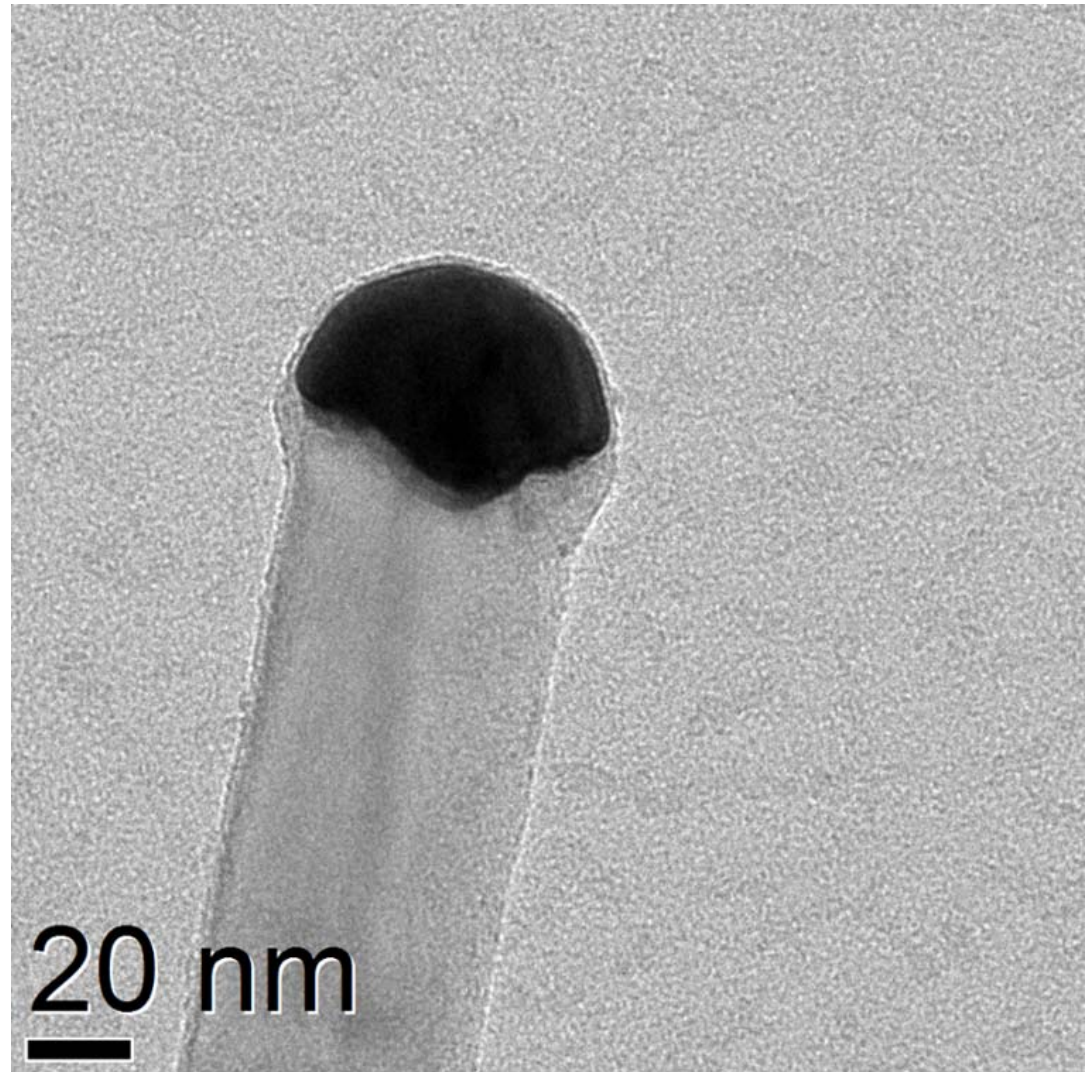


- high surface sensitivity
- ...surface details that could not be seen become visible

Courtesy: Carl Zeiss NTS, P. Gnauck

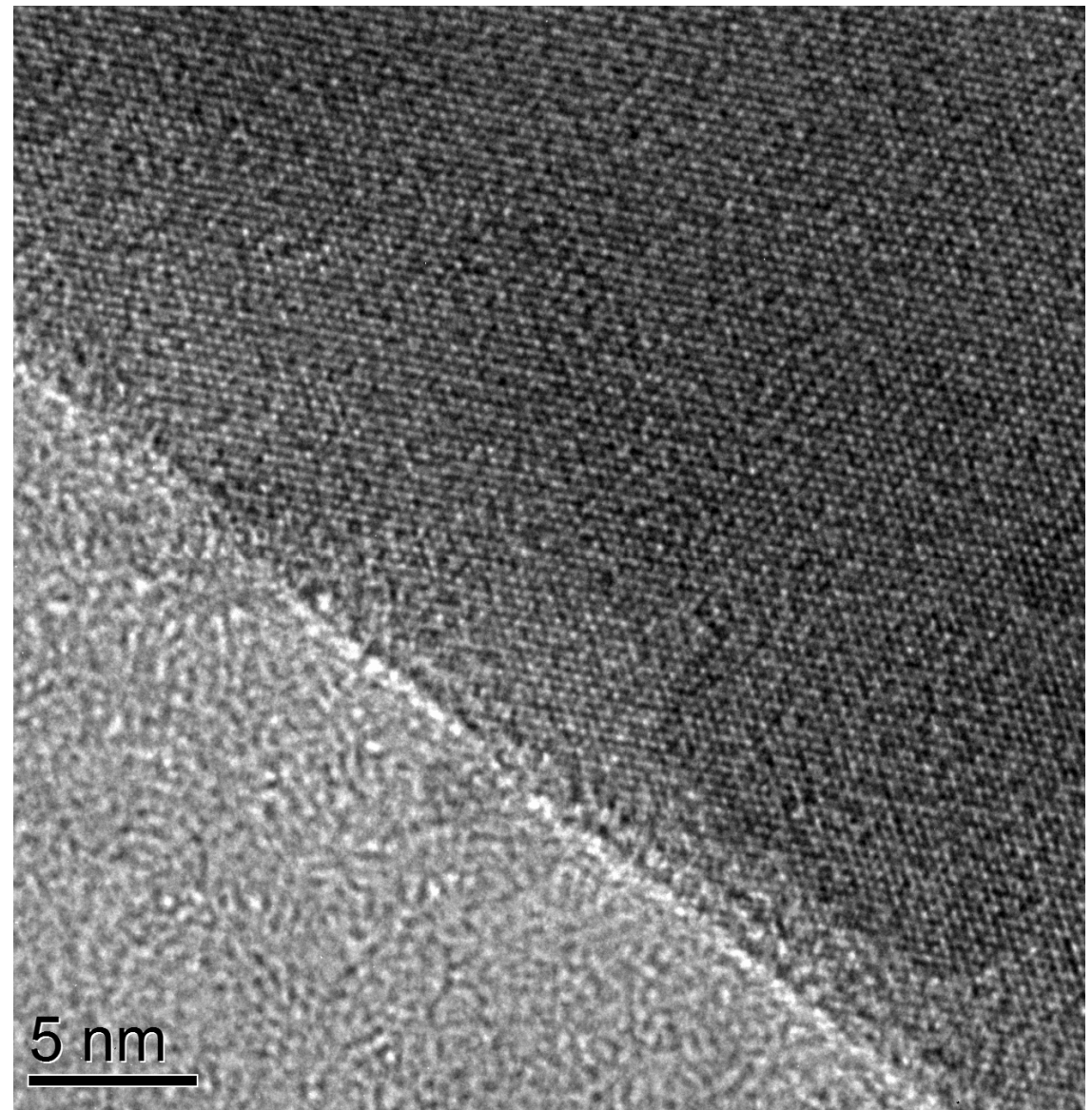
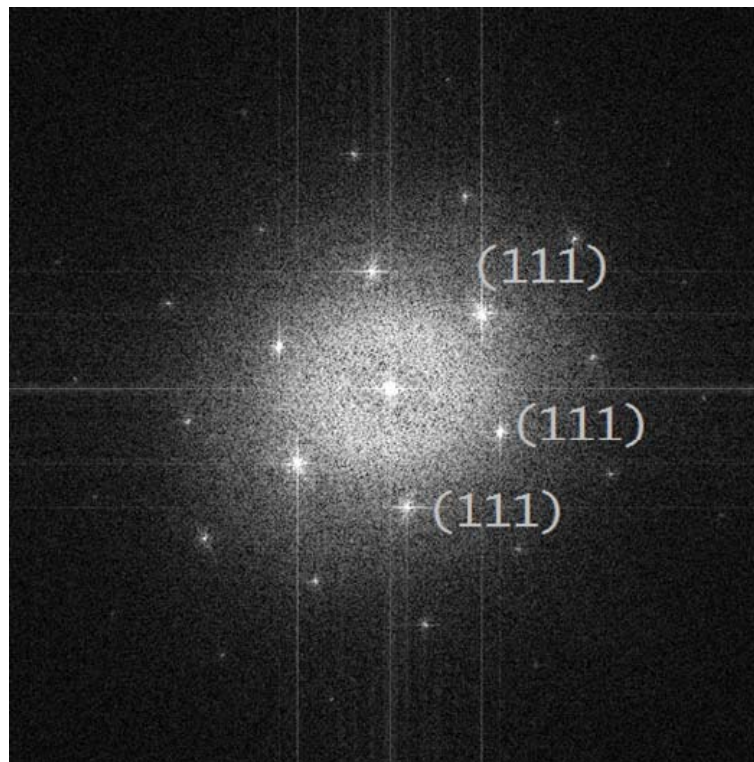
Methods of analysis Imaging: Transmission electron microscopy

Upper end of a silicon-nanowire
(futural electronic structures) with
a gold particle as seed

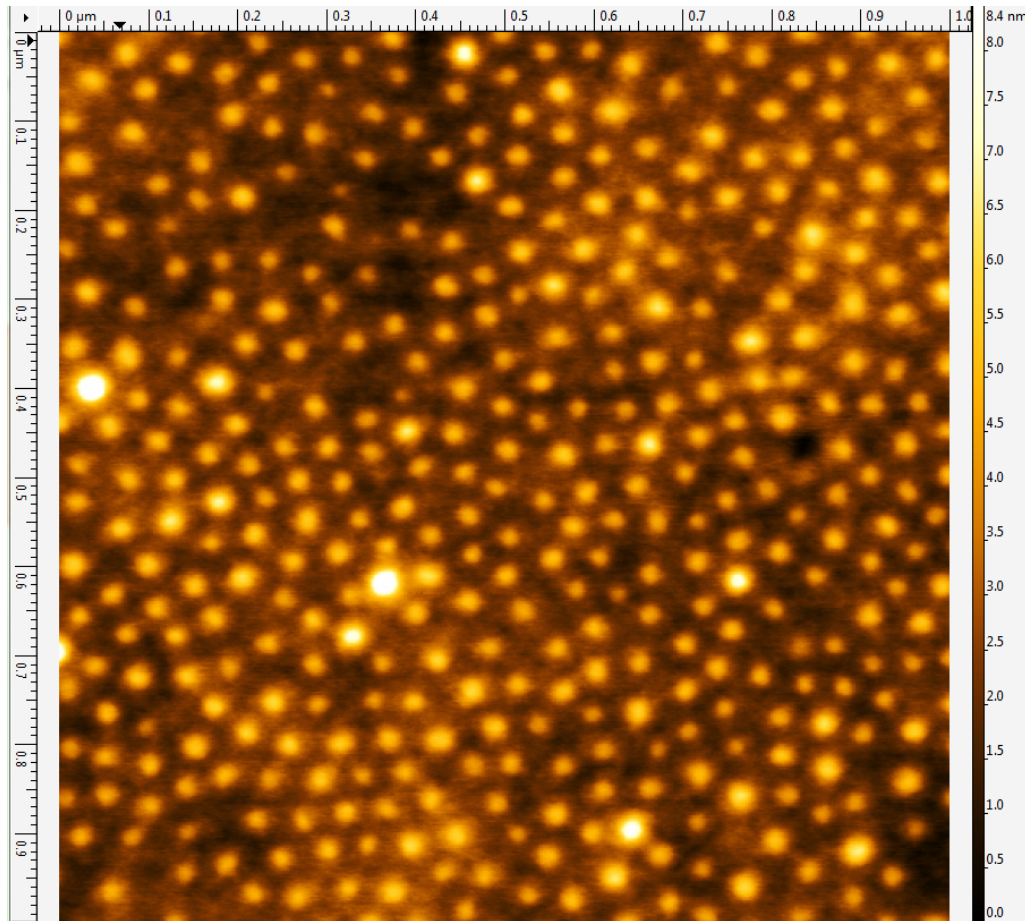


Methods of analysis Imaging: HR Transmission electron microscopy

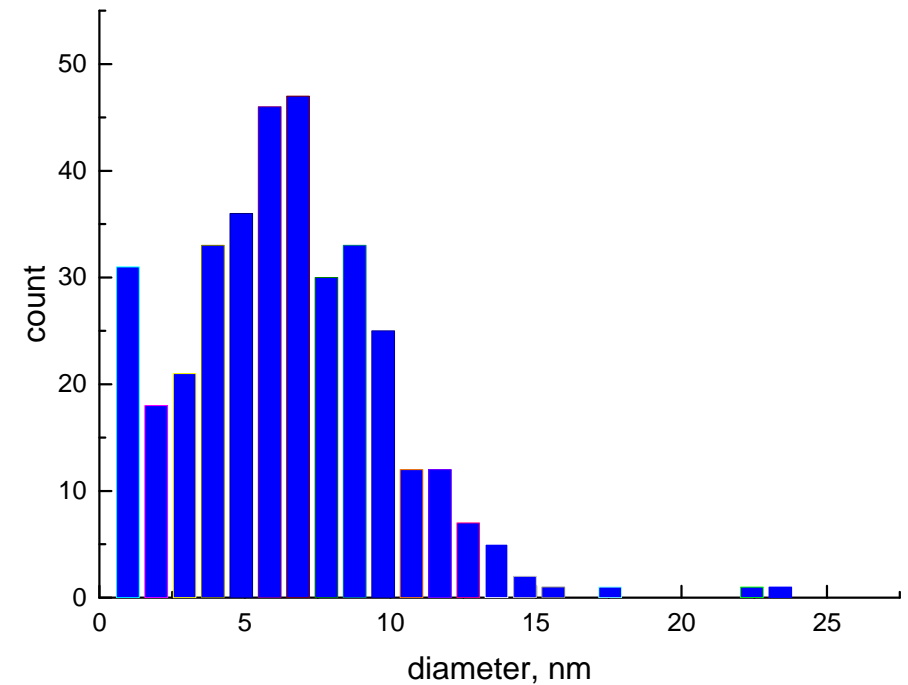
Sidewall of a silicon-nanowire in HRTEM for observation of growing direction and interface behaviour



Topography image (left) and size distribution (right) of a polymer material (foil)



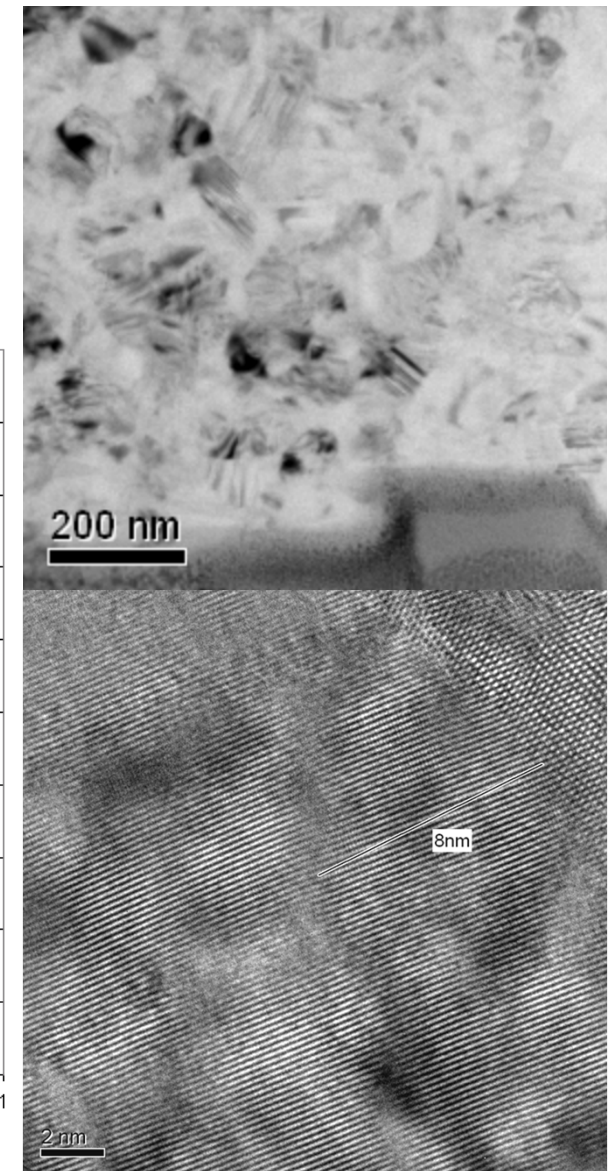
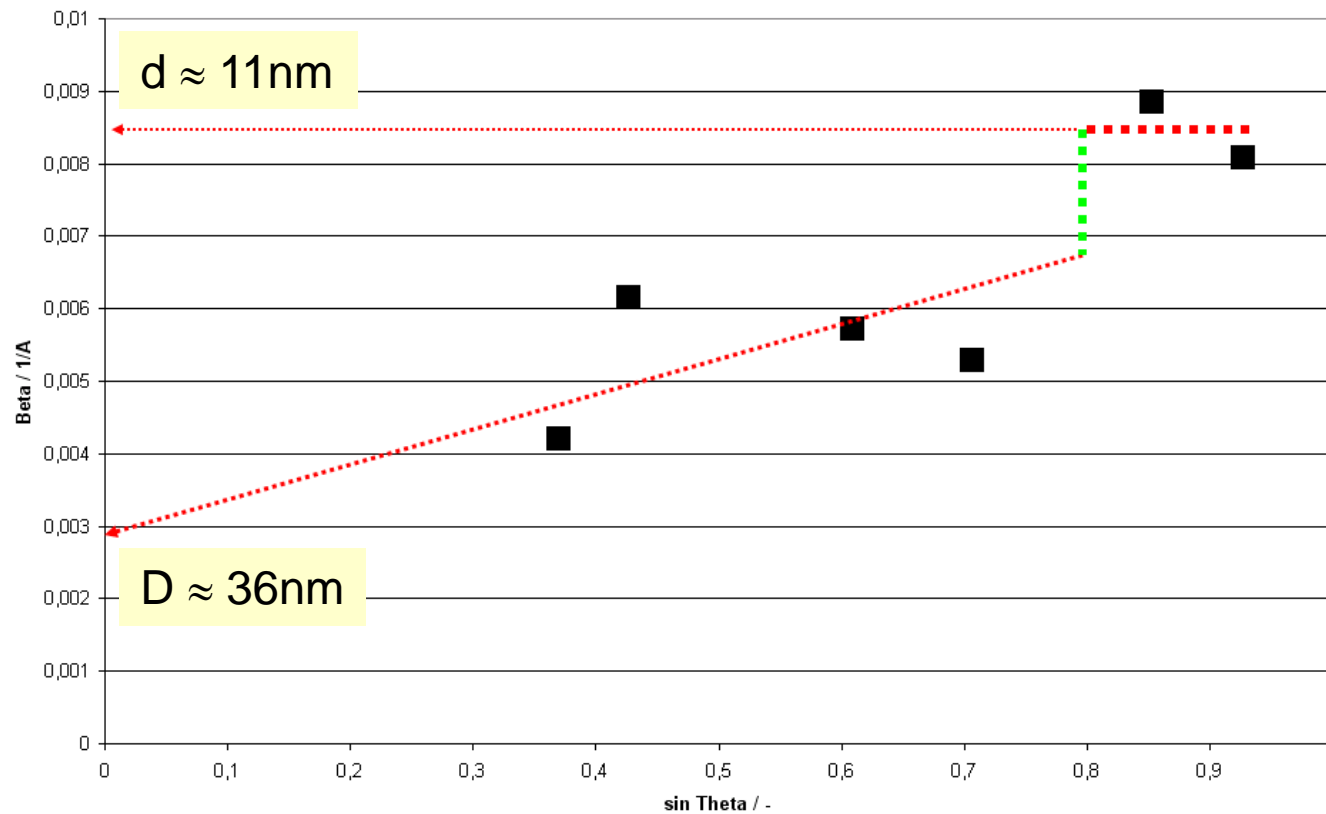
Sample: PS-b-P4VP
(*polystyrene-block-poly(4-vinylpyridine)*)



Courtesy: Leibniz-Institut für Polymerforschung Dresden e.V. + Dr. M. Kopyczunska-Mueller (IKTS-MD)

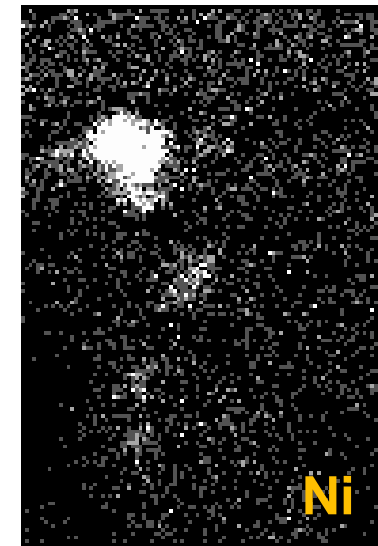
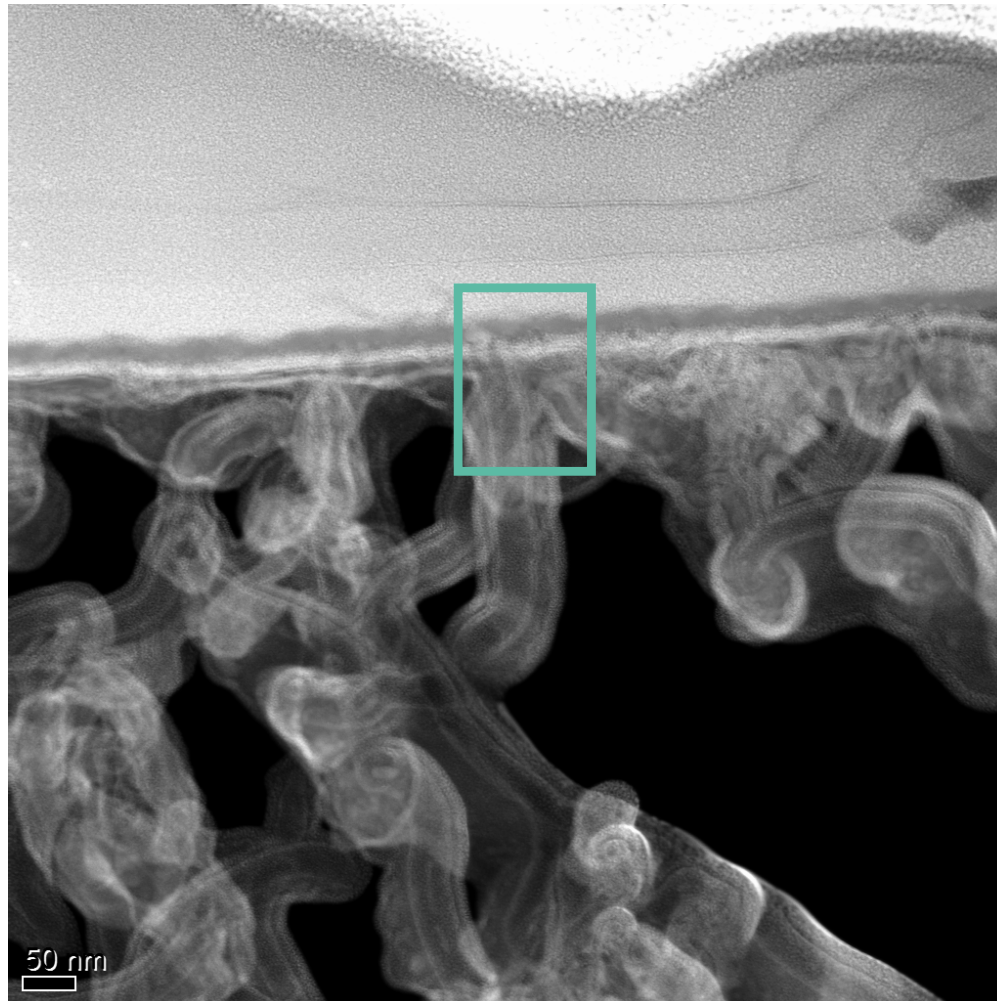
Methods of analysis Diffraction: X-ray Diffraction

X-Ray-Diffraction, Williamson-Hall-Plot:
Linebroadening over sin of diffraction angle (lower image)
characterizes mosaic structure



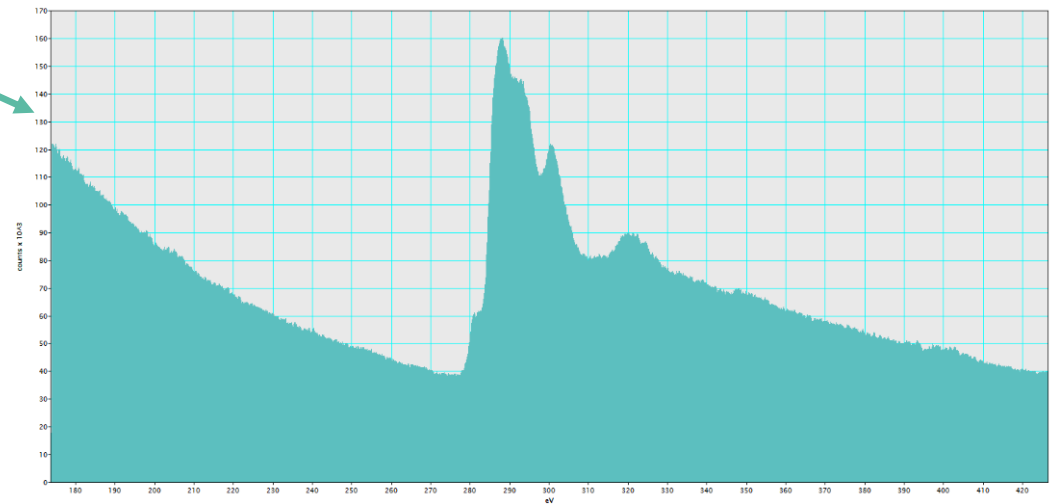
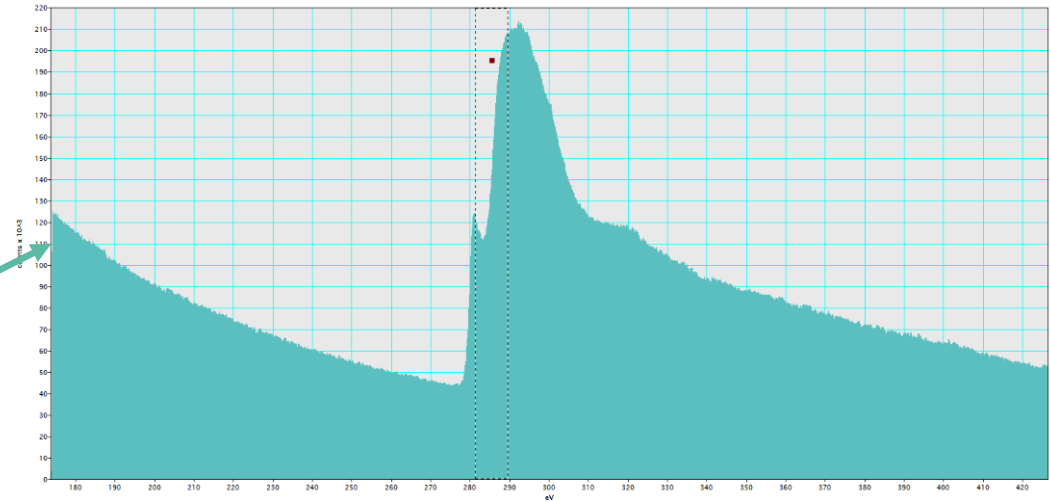
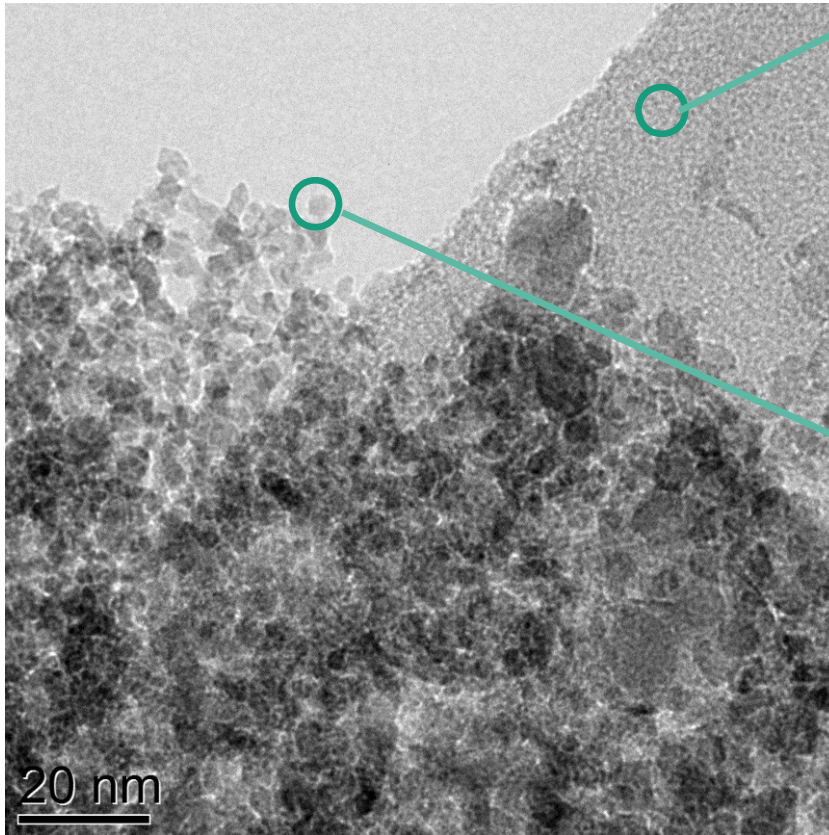
Methods of analysis Energy dispersive X-ray Spectroscopy (TEM)

Carbonnanotubes, Ni-particle as seed for growth process



Methods of analysis Electron Energy Loss Spectroscopy

Nanodiamonds on
an amorphous C-foil:
Imaging (lower image) and EEL-
Spectrum (K-edge of Carbon)



Methods of analysis

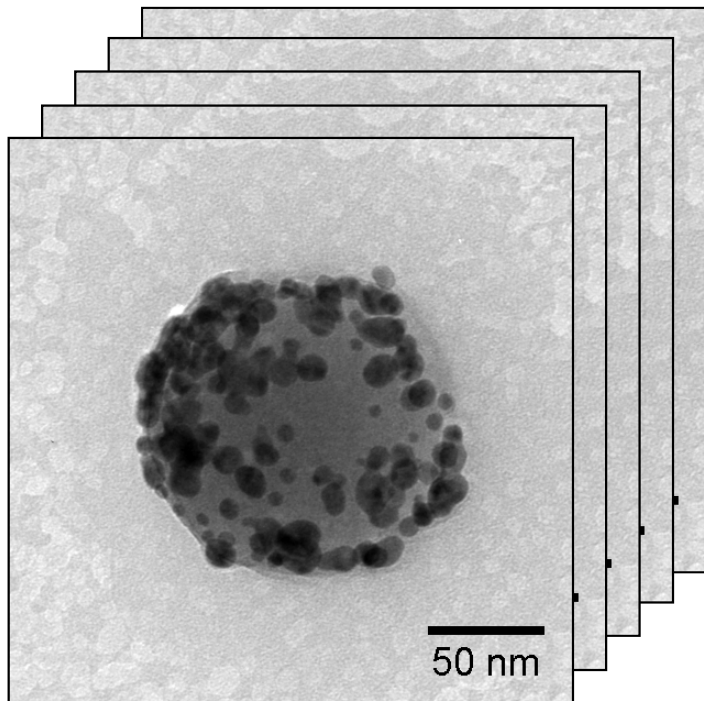
Electron Tomography

A 3D-world on the nanoscale: Example: Au nanoparticles on silica sphere

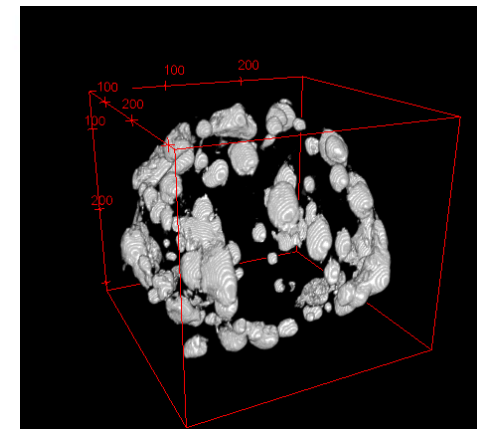
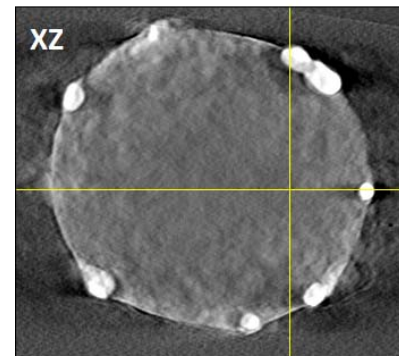
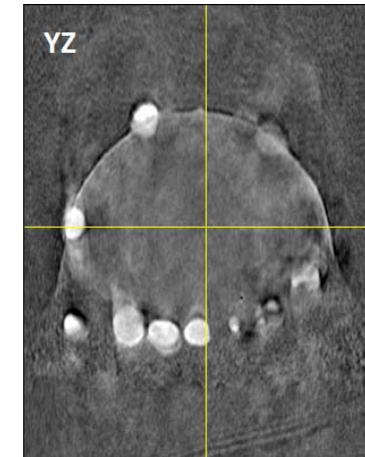
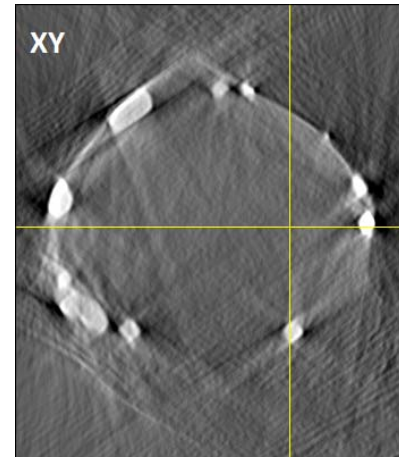
Recorded tilt series

range: -60° to $+60^\circ$

step: 1°



Reconstructed volume (WBP)



Summary

- For characterization of nanomaterials a large number of aspects might be of interest: Size, shape, structure, chemistry, crystallography, ...
- Due to the wavelength' electron microscopy in its different variations is most employed method for characterization of nanomaterials.
- Ion microscopy (Focused Ion Beam, Helium Ion Microscopy) are interesting and new add-ons.
- Spectroscopic methods and 3D-related methods (tomography) complete the results.

Analytical methods for characterization of nanomaterials

Contact person

Prof. Dr. Ehrenfried Zschech

Division Director, Fraunhofer Institute for Ceramic Technologies and Systems IKTS,
www.ikts.fraunhofer.de

Speaker, Dresden Fraunhofer Cluster Nanoanalysis, www.nanoanalysis.fraunhofer.de

Scientific Coordinator, Dresden Center for Nanoanalysis at TU Dresden, www.tu-dresden.de/dcn

Past President, Federation of European Materials Societies FEMS, www.fems.org

Fraunhofer Institute for Ceramic Technologies and Systems IKTS
Maria-Reiche-Strasse 2

D-01109 Dresden
Germany

Phone +49 351 88815 543

Fax +49 351 88815 509

Email ehrenfried.zschech@ikts-md.fraunhofer.de

Analytical methods for characterization of nanomaterials

Contact person

Dr. Ing. Habil. Uwe muehle
Mikro- and Nanoevaluation
Fraunhofer Institute for Ceramic Technologies and Systems
Materials Diagnostic

Maria-Reiche-Str. 2
01109 Dresden
Germany

Phone: +49 351 88815 547
uwe.muehle@ikts-md.fraunhofer.de

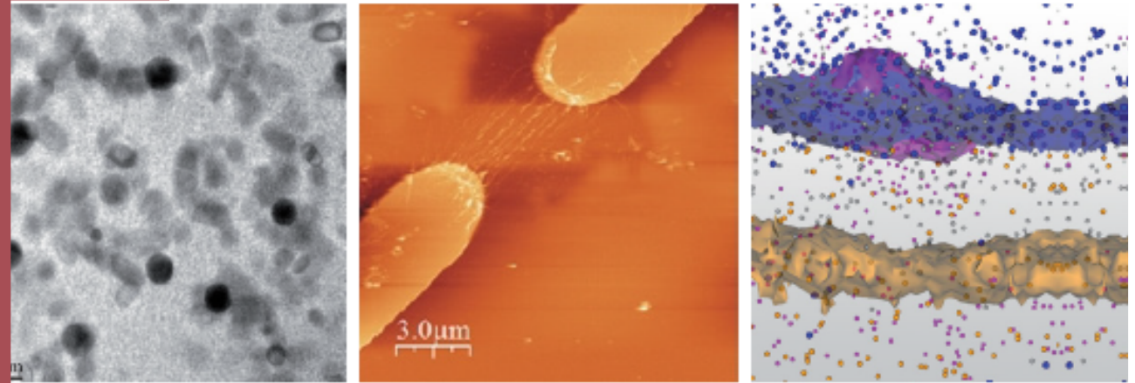
European Advanced Training Course

Nano-scale Materials

Characterization-Techniques
and Applications

9 - 11 June 2015, Dresden,
Germany

Dresden Fraunhofer Cluster Nanoanalysis (DFC)



For further information please contact:

Deutsche Gesellschaft für Materialkunde e.V.

Susanne Grimm · Hahnstraße 70 · D-60528 Frankfurt, Germany

T +49 (0)69 75306-757 · Zentrale +49 (0)69 75306-750

F +49 (0)69 75306-733 · fortbildung@dgm.de · www.dgm.de

Analytical methods for characterization of nanomaterials

E. Zschech

Survey of analysis techniques for multiscale materials characterization

E. Langer and S. Mucke

Imaging and element analysis of materials: Scanning electron microscopy and focused ion beam technique

- Introduction to SEM and FIB - Application in industry: Si-based and organic micro- electronics - Challenges and limits of the techniques

U. Muehle and M. Loeffler

Atomic resolution studies of materials and interfaces: Transmission electron microscopy - Imaging: Setup and contrast mechanisms - Structure and strain analysis: Diffraction techniques - Elemental analysis: EDX and EELS/EFTEM - Electron tomography - In-situ studies

P. Konda Gokuldoss

3D atomic structures in nanoscale materials: Atom probe tomography - Experimental and analysis techniques - Sample preparation with focused ion beam - Application in materials science and nanoelectronics

J.-U. Schmidt and J. Heber

Thin film analysis: Optical analysis and metrology, X-ray reflectometry

- Ellipsometry
- Interferometry
- Application to photonic microsystems

L. M. Eng

High-resolution studies of surface topography and near-surface properties: Scanning probe microscopy

- High-resolution structure analysis in semiconductors: Dopand profiles
- Mechanical strain fields in semiconductors
- Magnetic nanofields in magnetic thin films and nanoparticles
Structures and fields at atomic dimensions

A. Clausner

Mechanical properties of nano-scale materials and thin films: Nanoindentation and related techniques

- Hardness, Young`s modulus and yield stress of nano-structures
- Nano-scale behavior of metals, ceramics, and glasses
- Properties and structure of nano-porous materials

J. Gluch and M. Loeffler

3D imaging of materials: Micro- and nano X-ray tomography

- X-ray tomography: from micro to nano
- Resolution and field of view
- Lab-based systems vs. synchrotron research
- Applications in materials science, electronics and biology